



Tektronix

New application and test introduction

KEITHLEY
A Tektronix Company

Outline

- 2D materials and devices
- NVMs
- CMOS characterization
- WBG
- 3D sensing

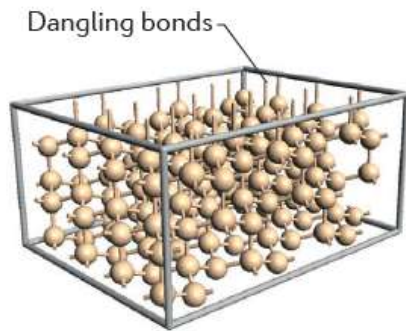
2D materials and devices



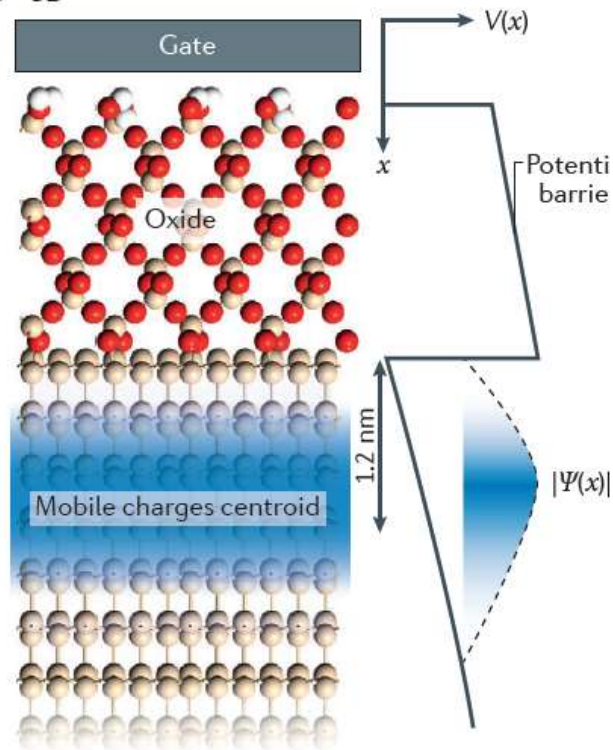
2D materials and devices

INTRODUCTION

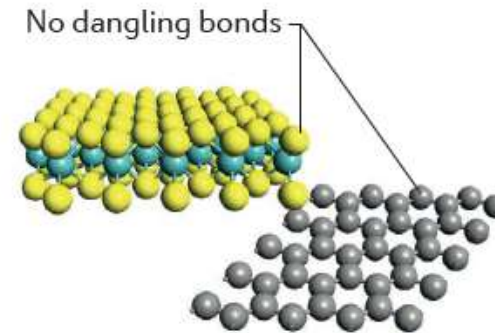
a Bulk materials



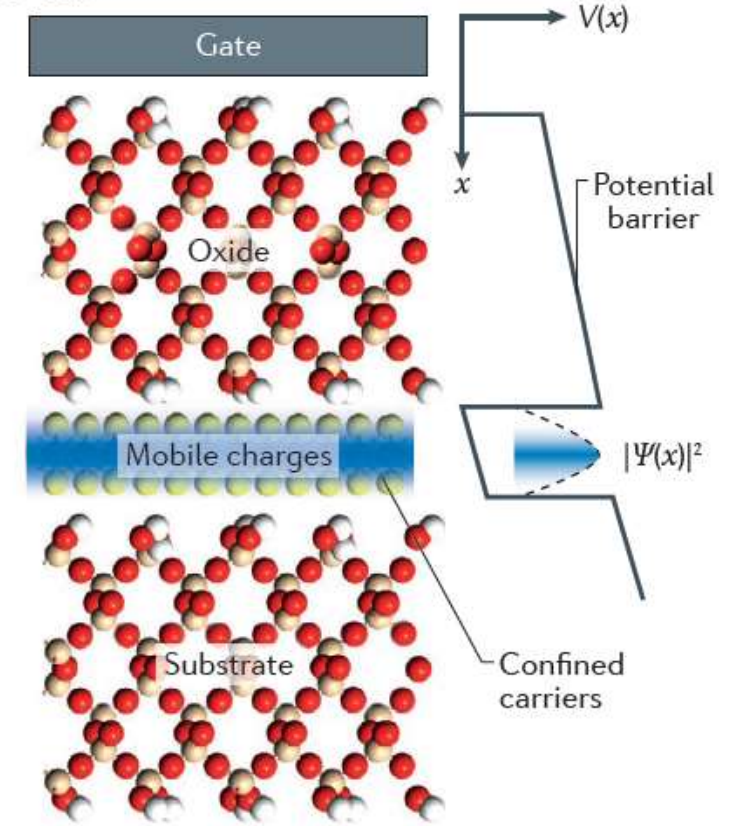
b 3D



c 2D materials



d 2D



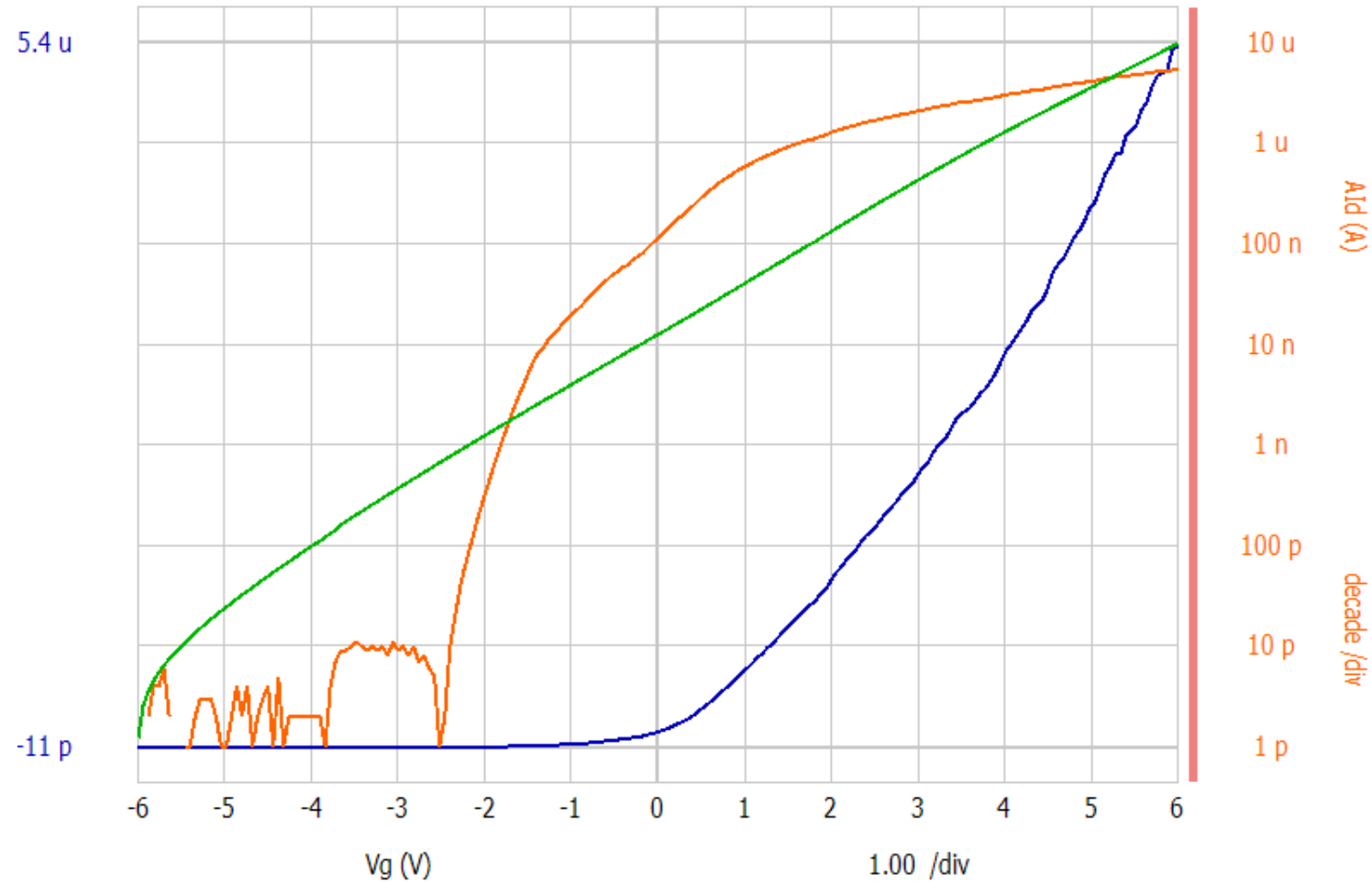
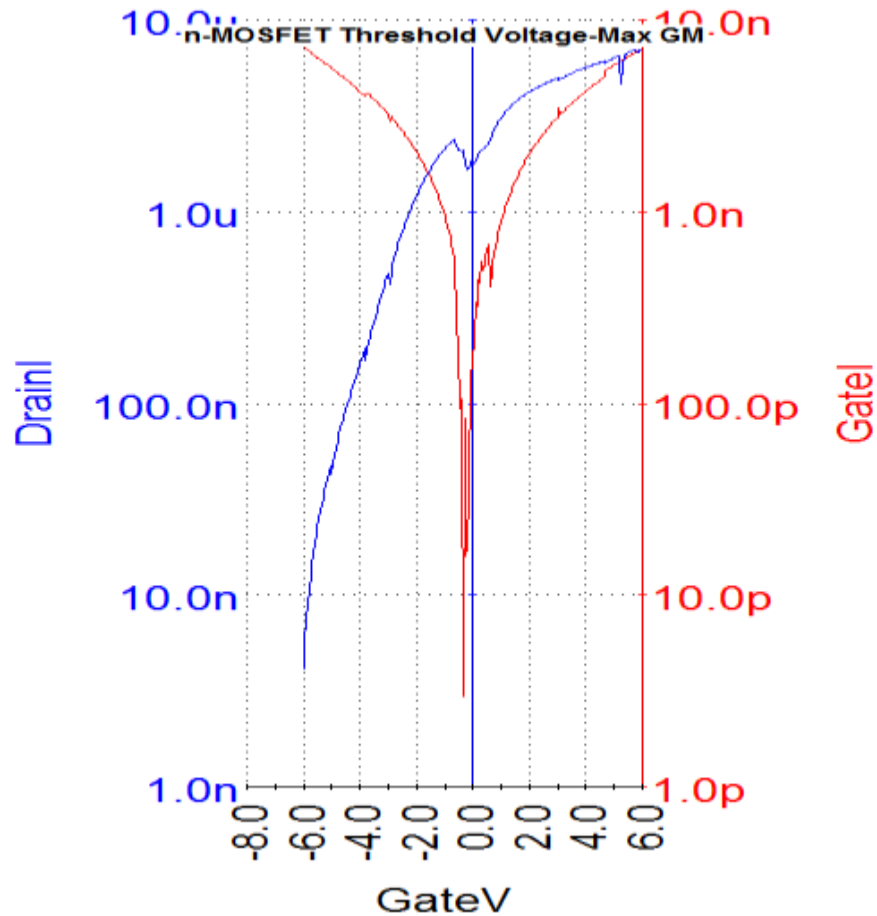
Two-dimensional semiconductors for transistors ; Manish Chhowalla^{1,2}, Debdeep Jena^{3,4} and Hua Zhang⁵ ; NATURE REVIEWS | MATERIALS

2D materials and devices

I-V TEST TECHNIQUE

- Which one is better?

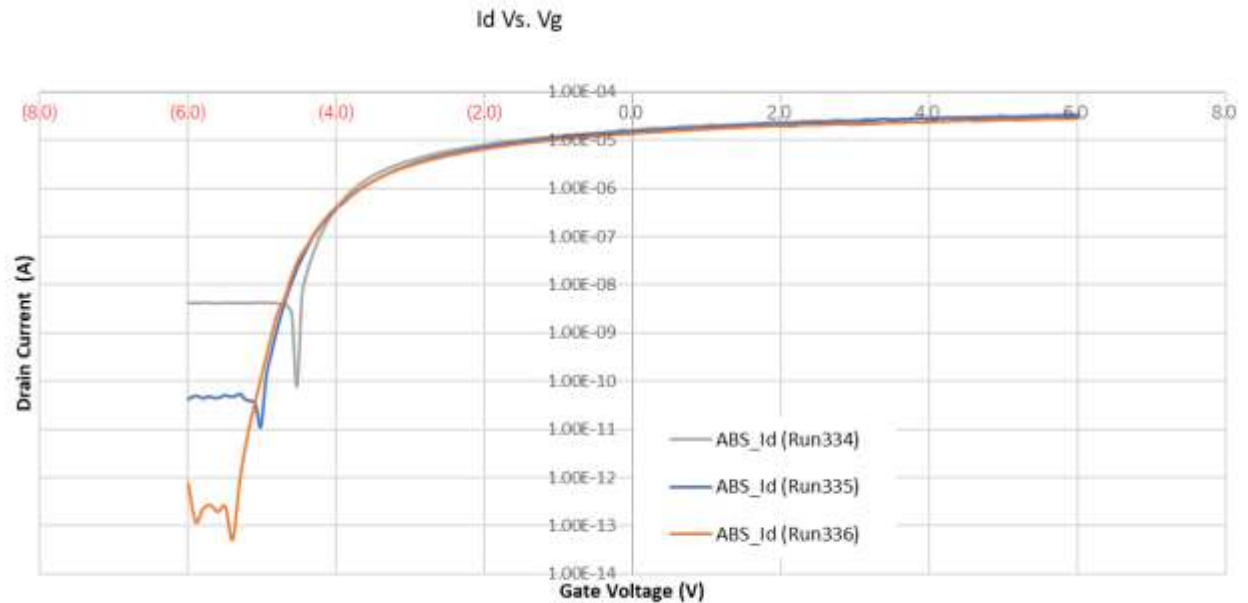
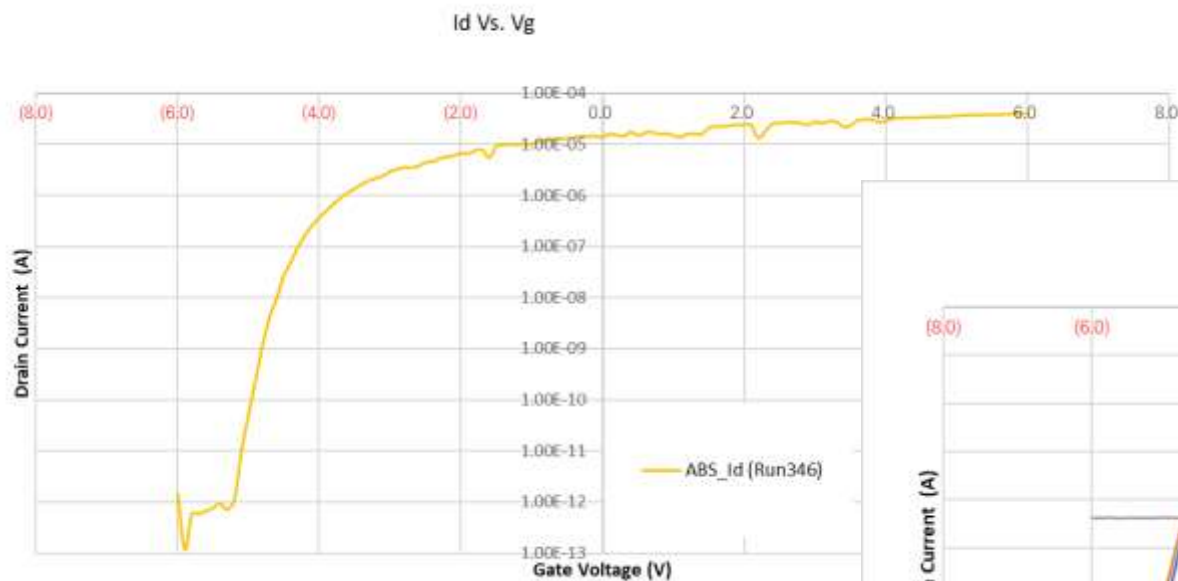
09/26/2017 10:01:35



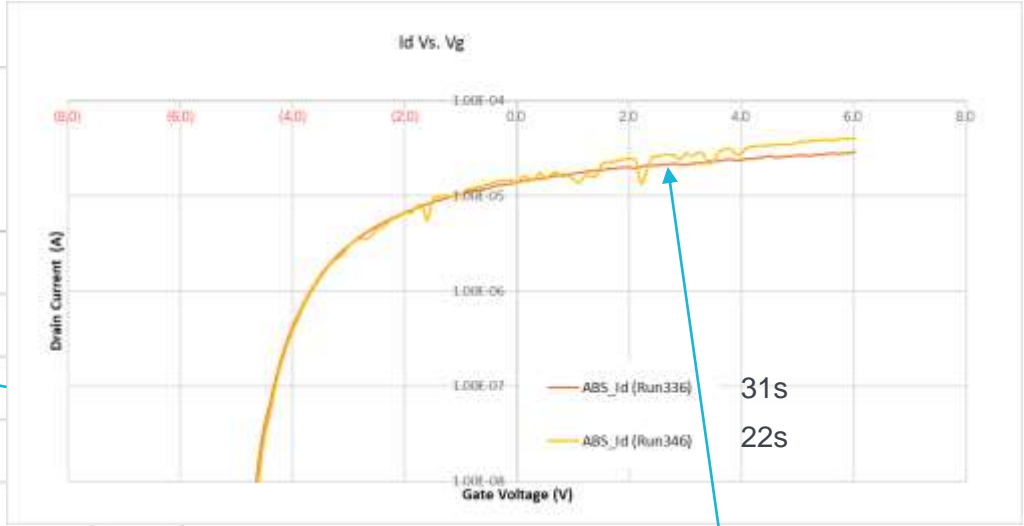
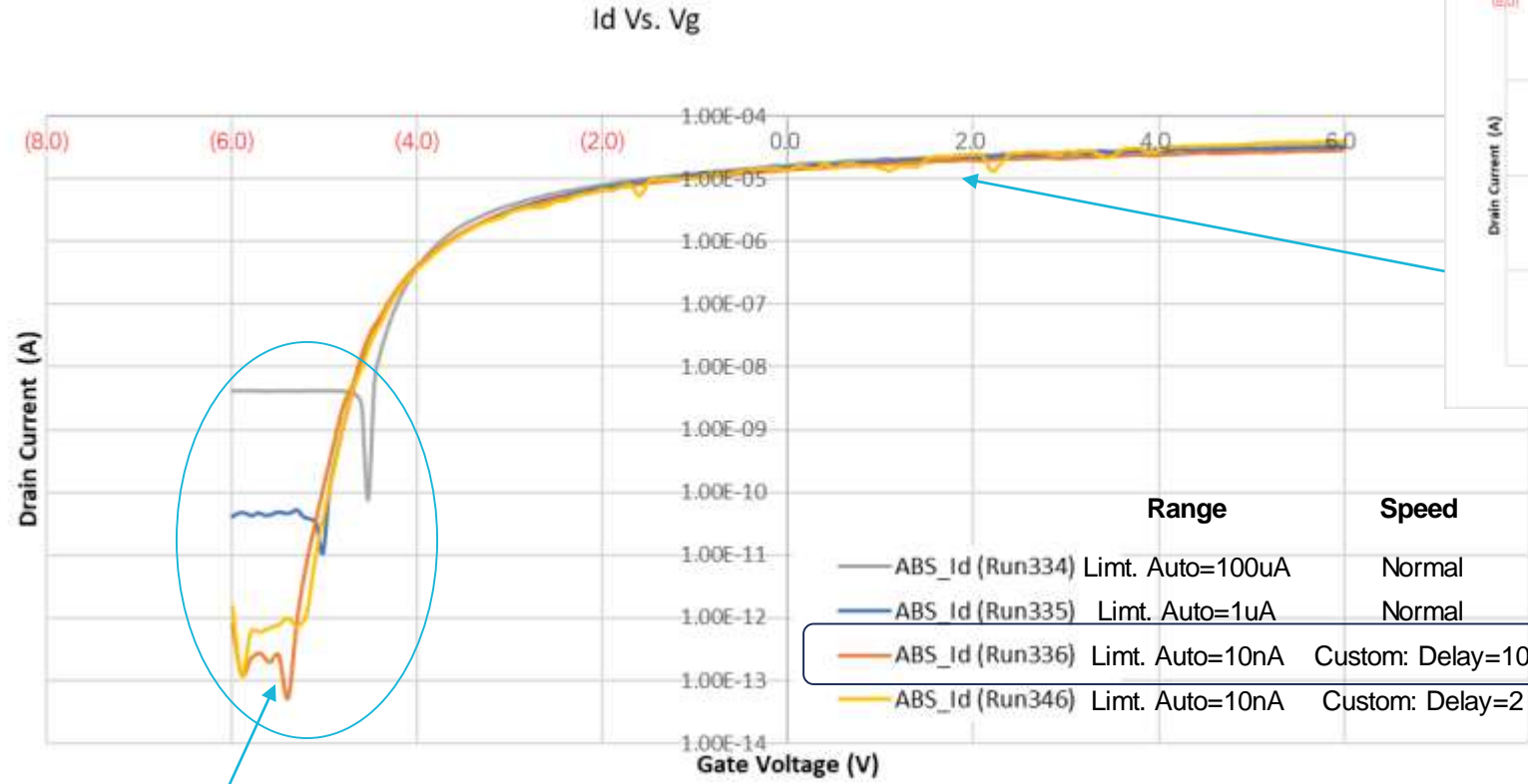
2D materials and devices

I-V TEST TECHNIQUE

- Which one is better?



Data

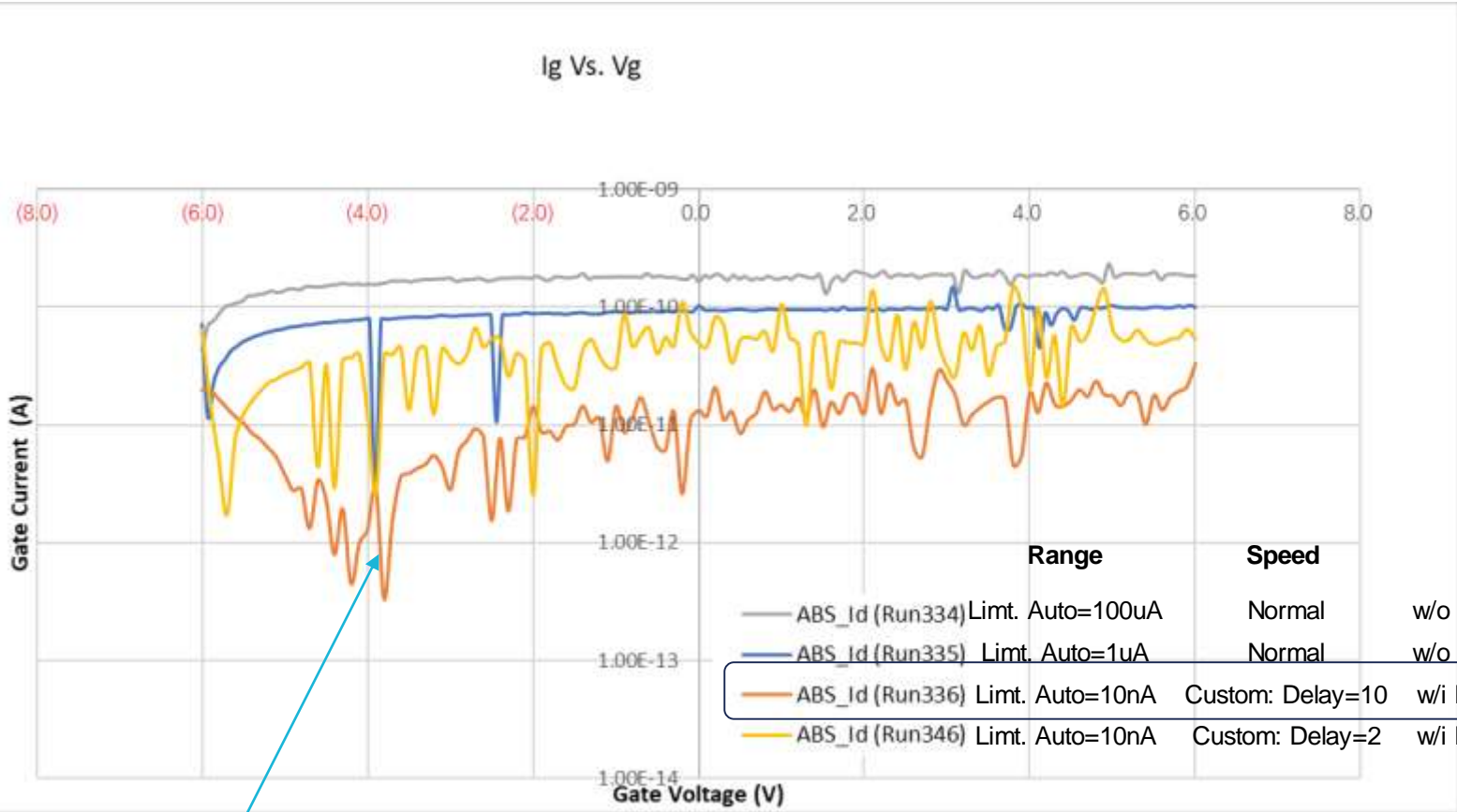


Lowest Ioff as DUT it is.

Delay factor should be bigger than 10, so that Drain current can be well settled. While, the test duration is not increased obviously.

Best test setting

Data



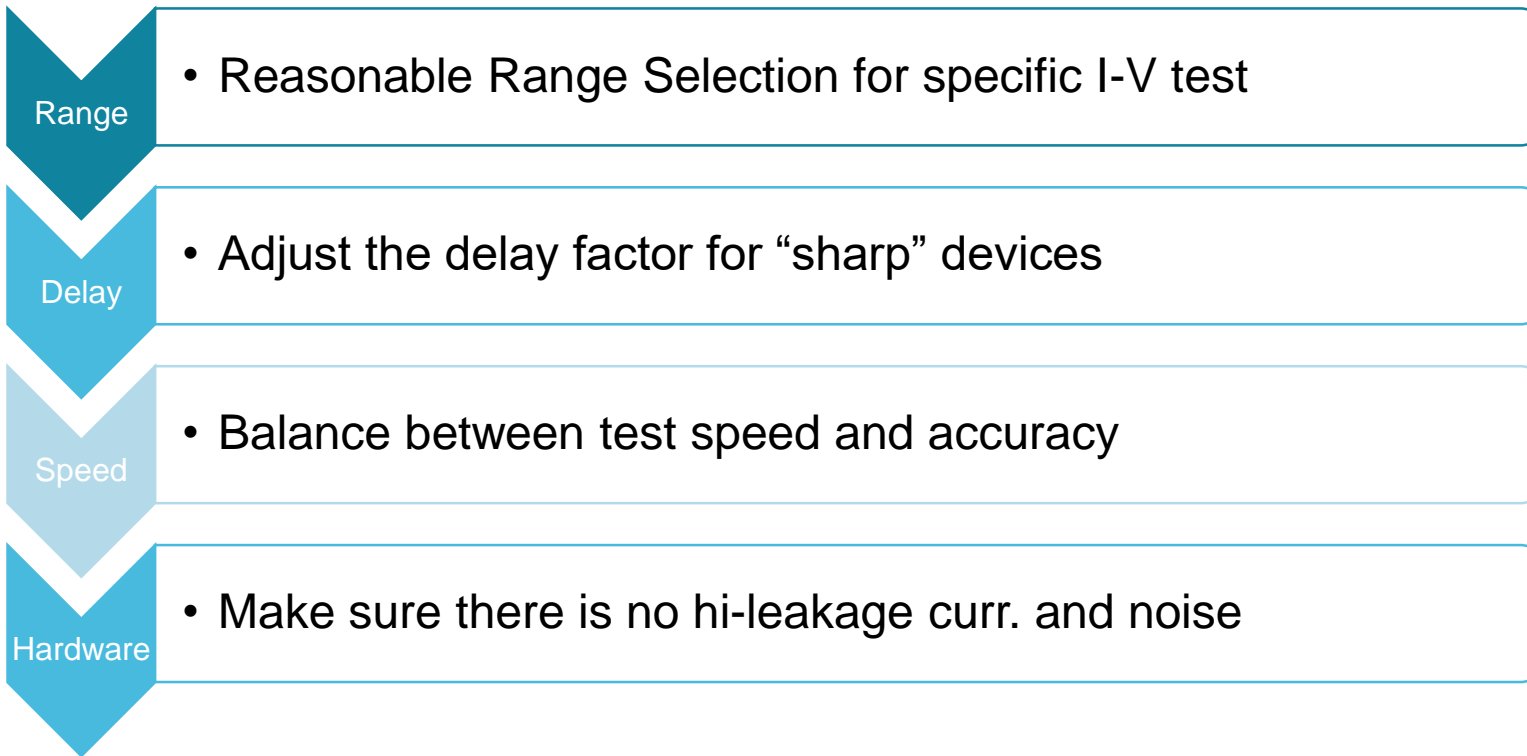
Lowest Ig as DUT it is.

Best test setting

2D materials and devices

I-V TEST TECHNIQUE

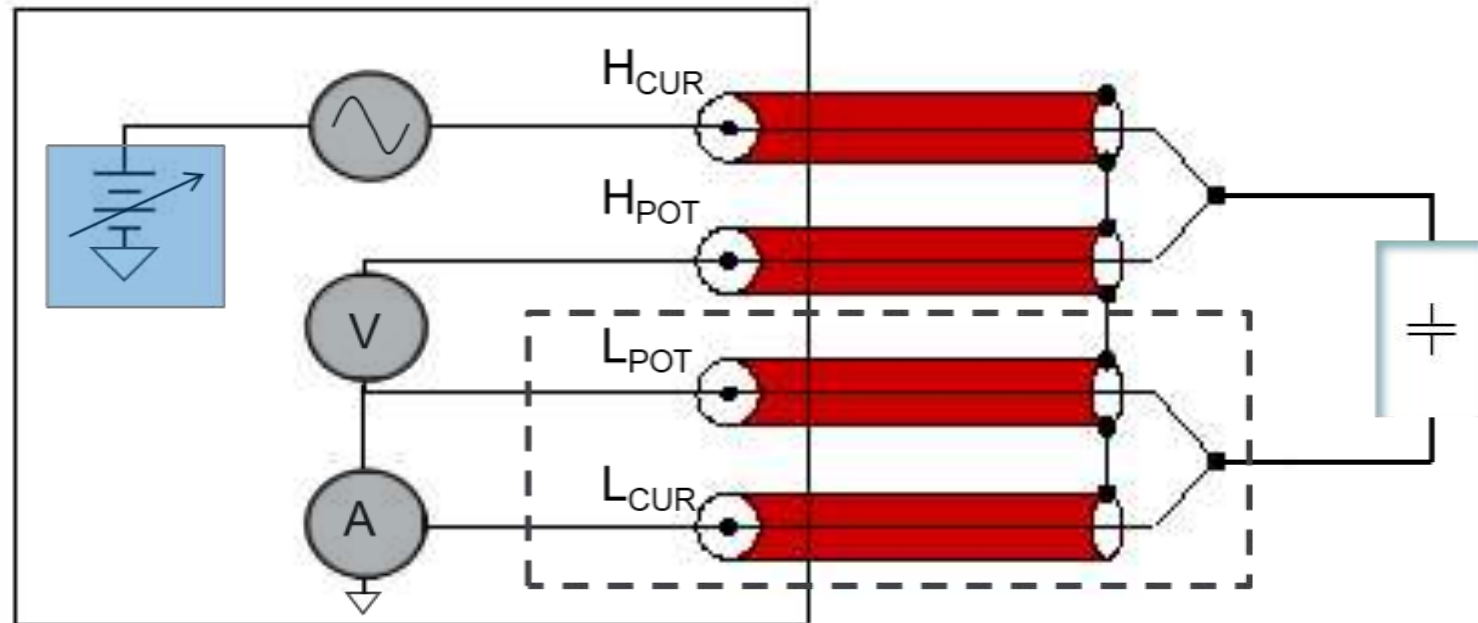
- What matters for IV test?



2D materials and devices

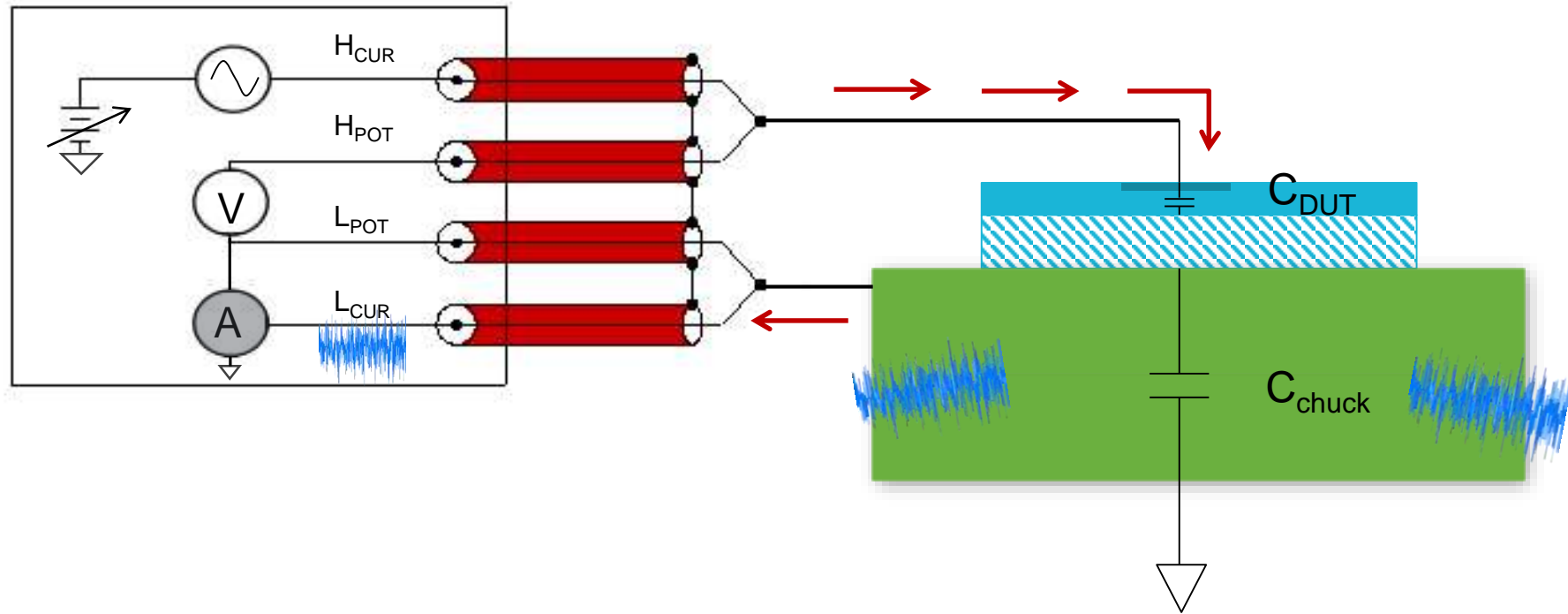
C-V TEST TECHNIQUE

Auto-balance Bridge with 4 Terminal Pair Configuration



Measuring C on a Wafer and Probe Station

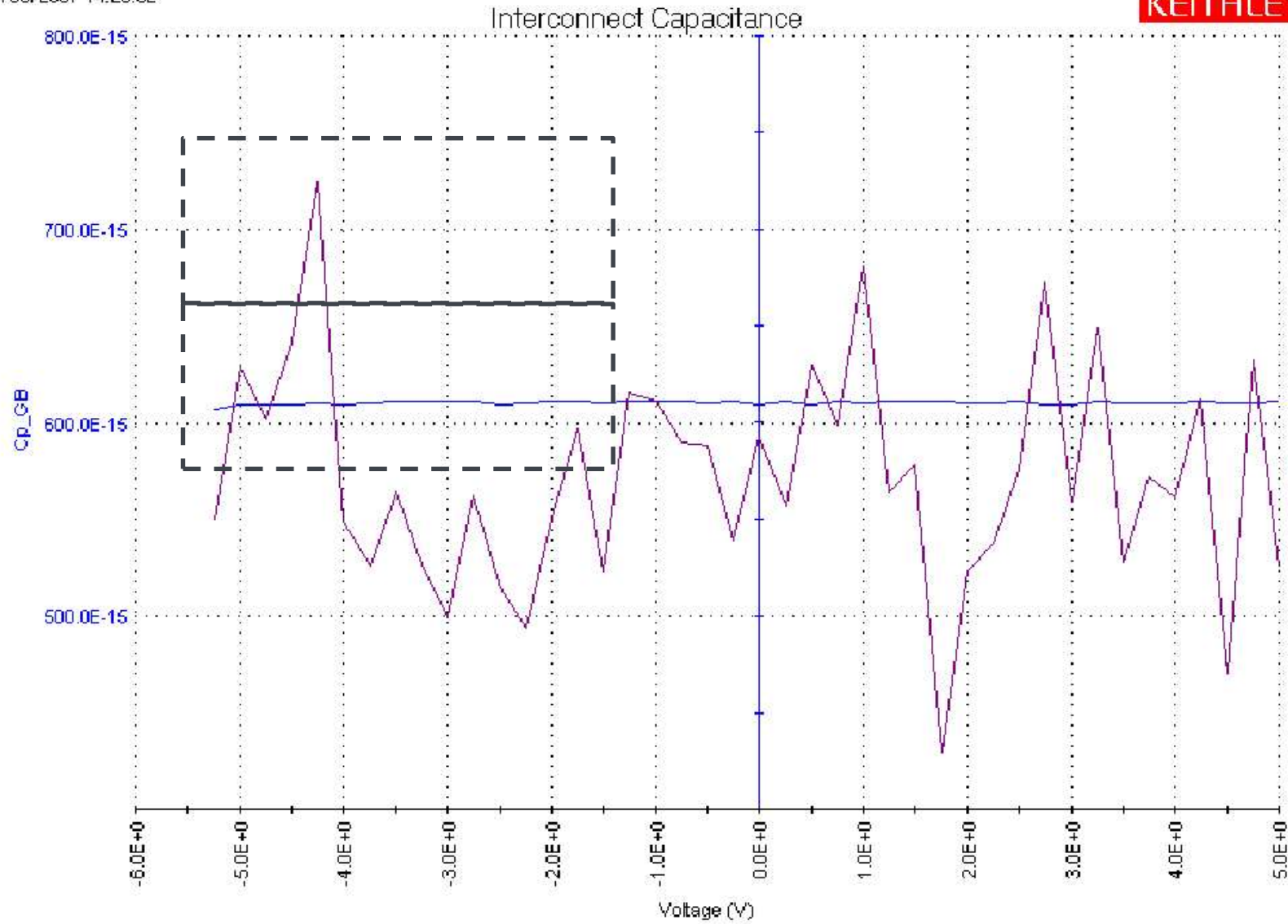
#1: Connect AC Ammeter to Least Noisy DUT Terminal



Exam

08/30/2007 14:29:32

KEITHLEY

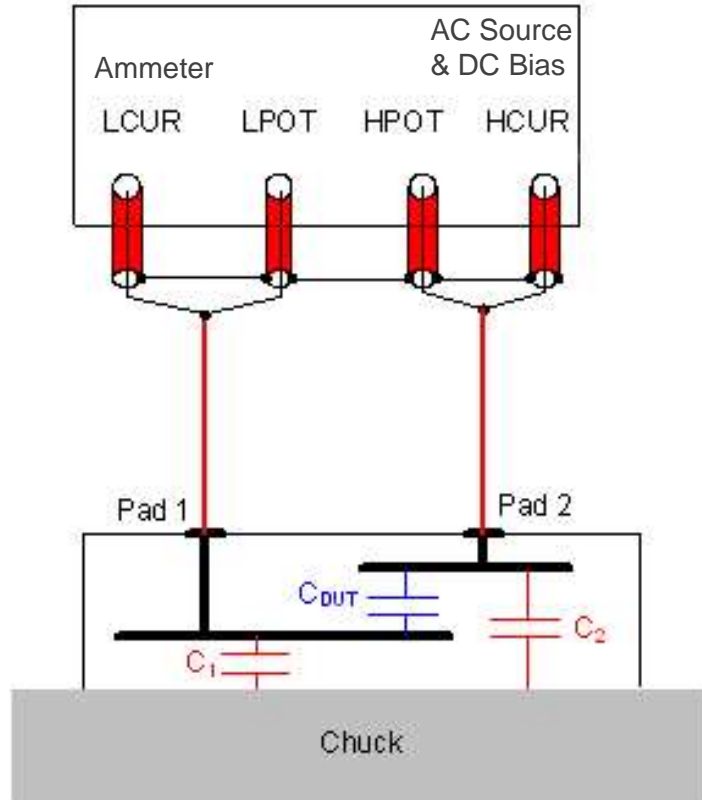


Data Variables
Data: NOISE = 836.63e-18

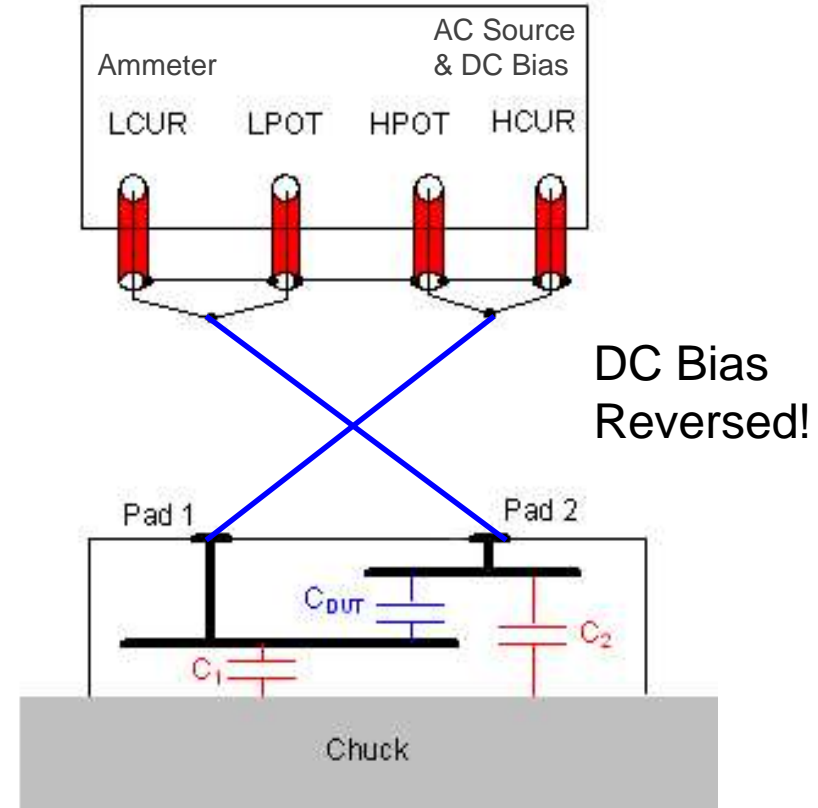


Switch High and Lo Leads

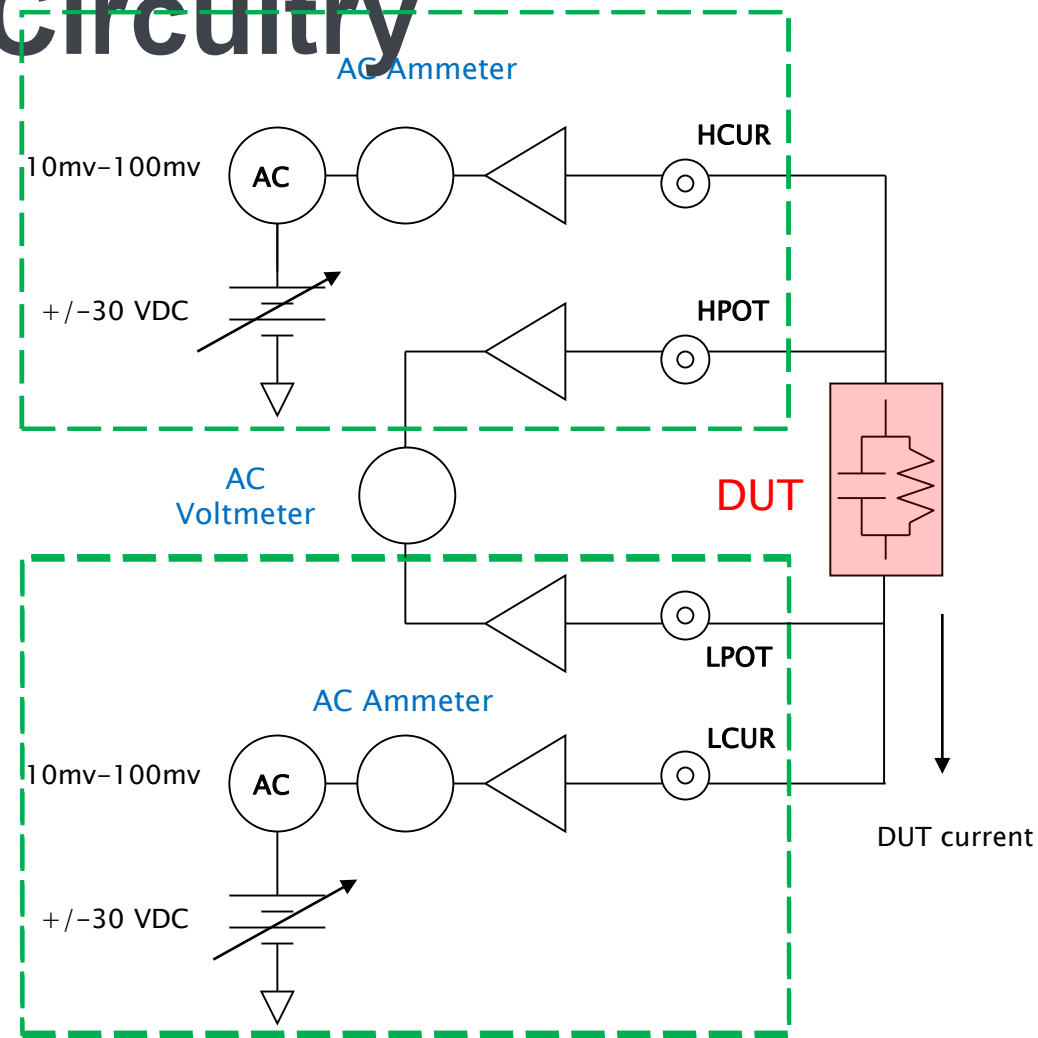
Noisy measurement connection scheme



Terminal connections switched

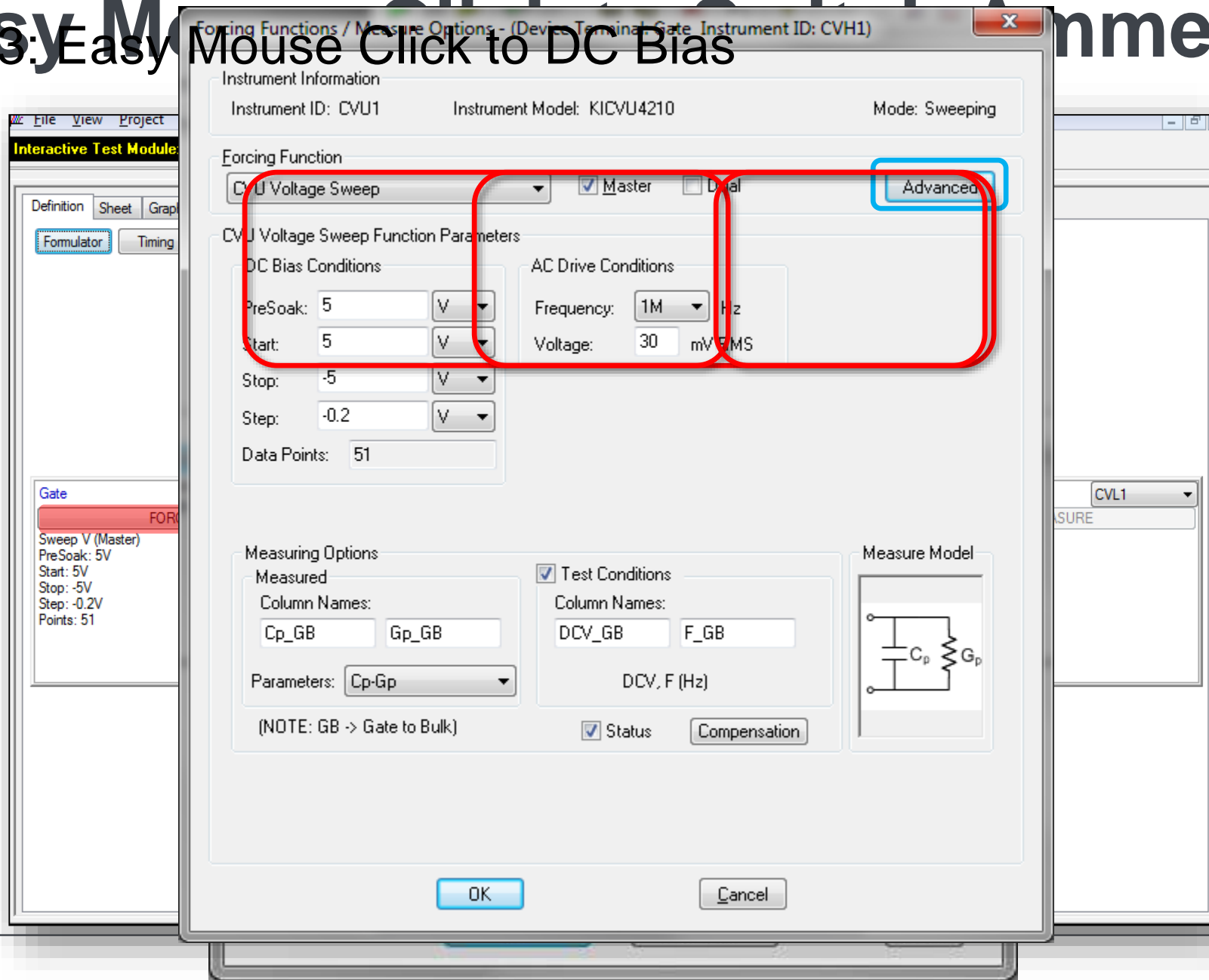


Keithley Improved the C-V Meter with Symmetrical Circuitry

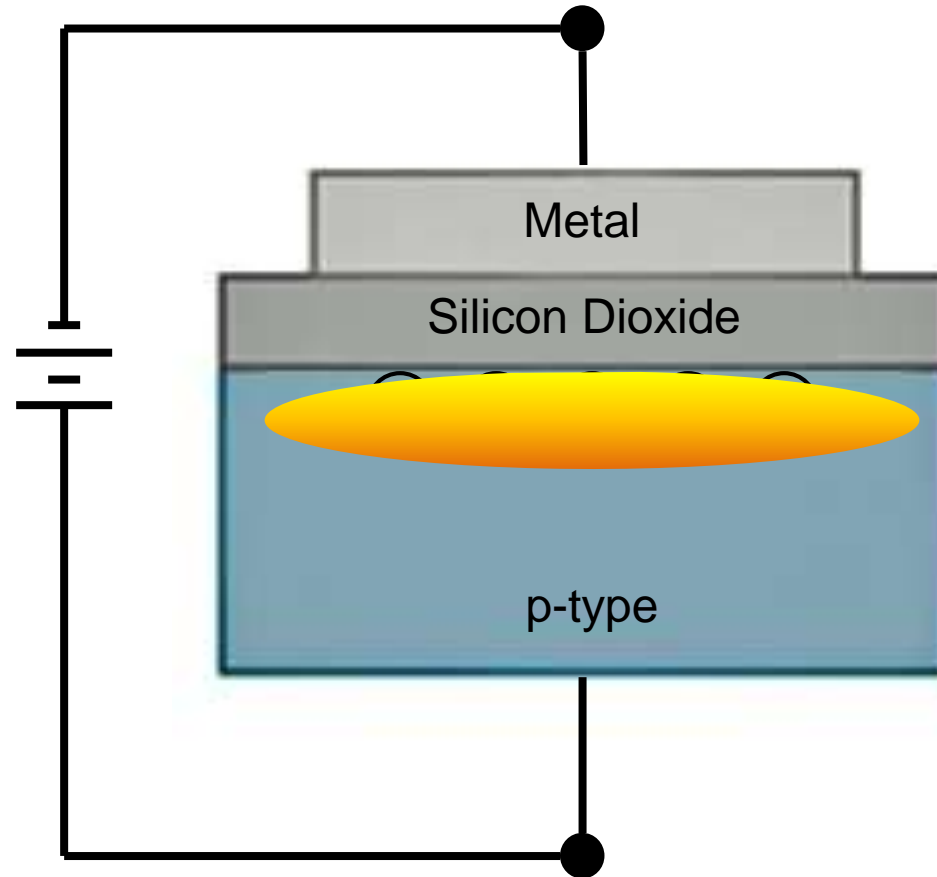


#2: Easy Mouse Click to DC Bias

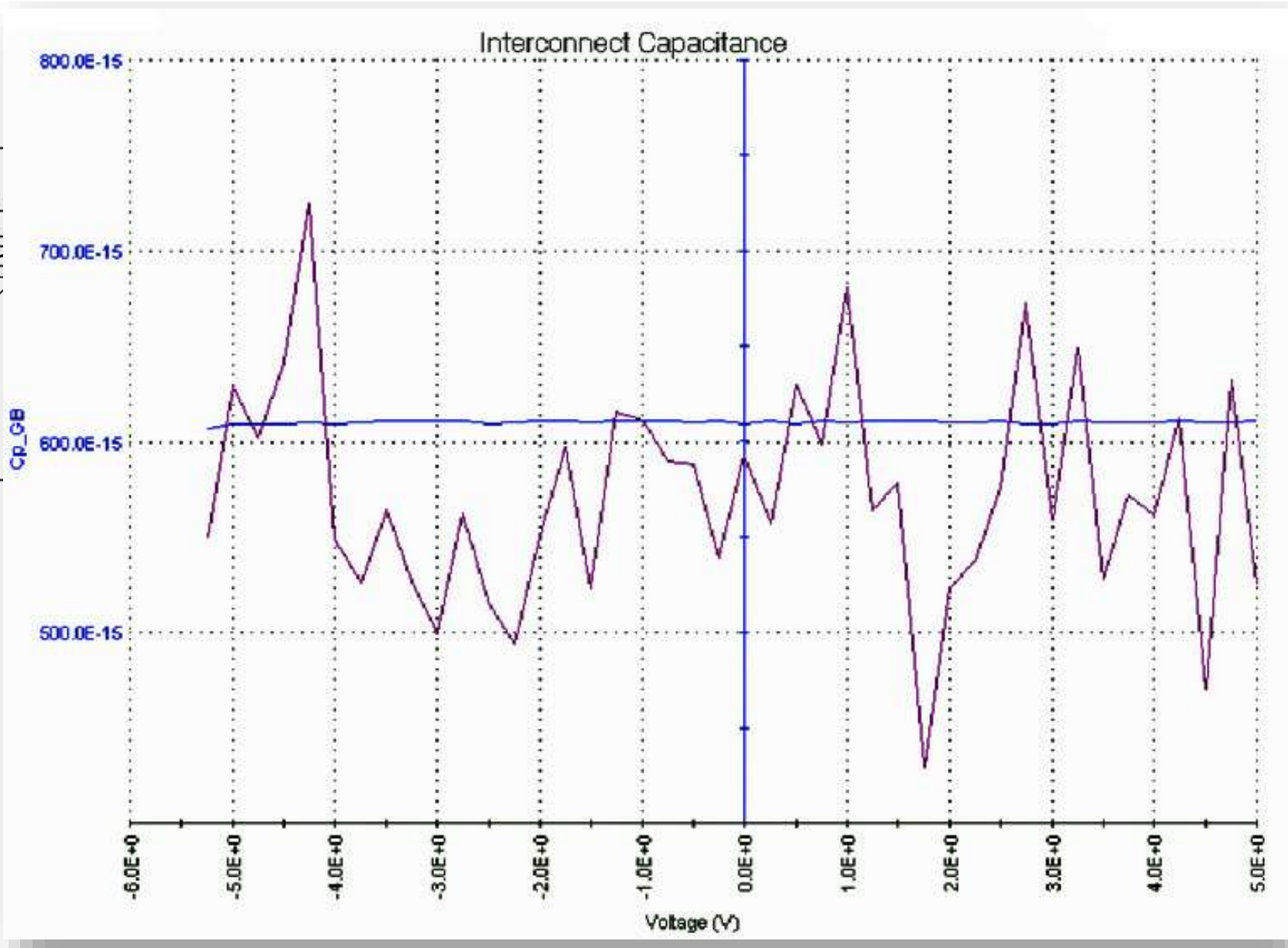
#3: Easy Mouse Click to DC Bias



Control of DC Bias Provides Precise Control of Electric Field



ΔH_{IL}
CP_GB

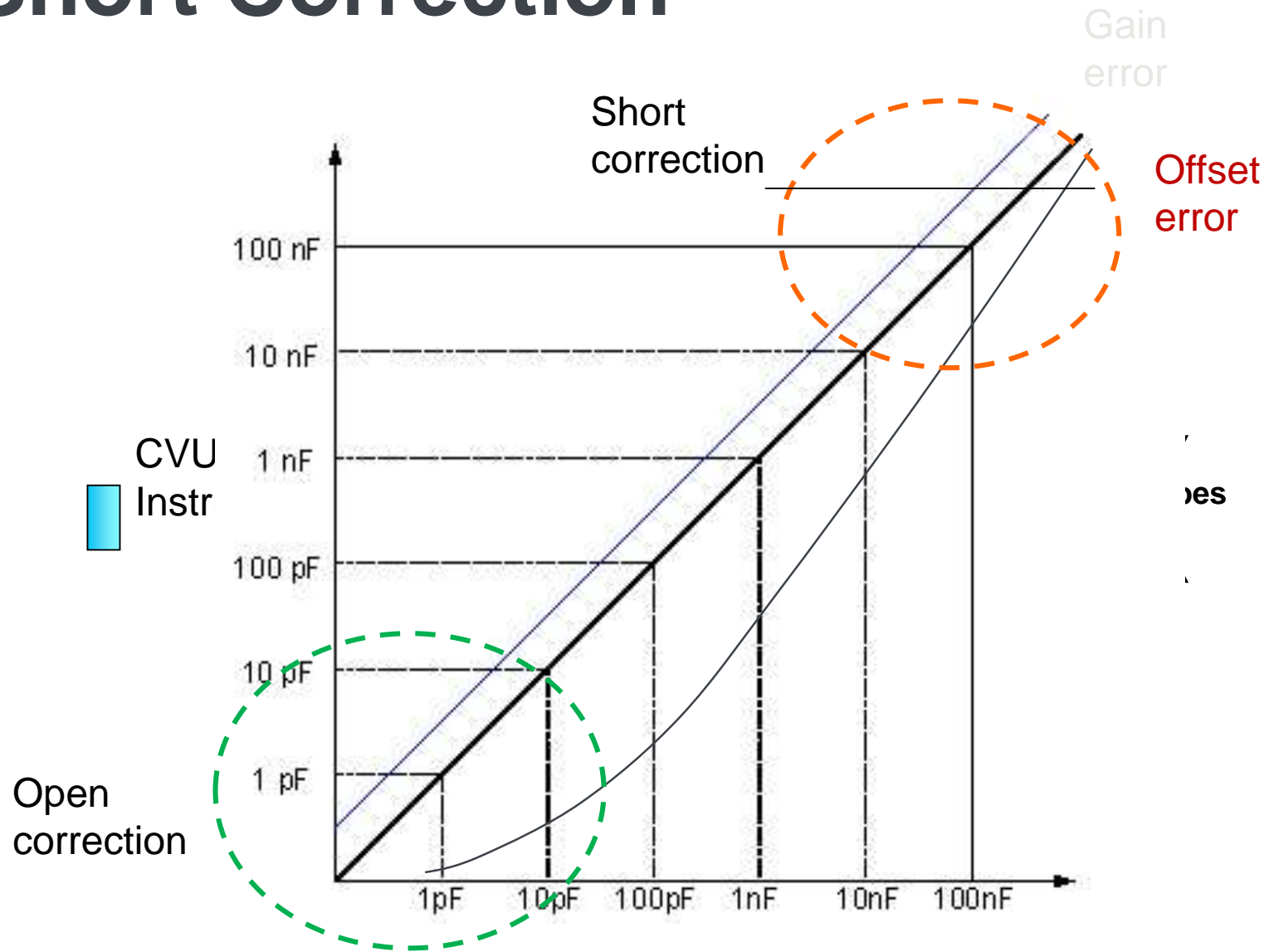


Confidence in Your Measurements



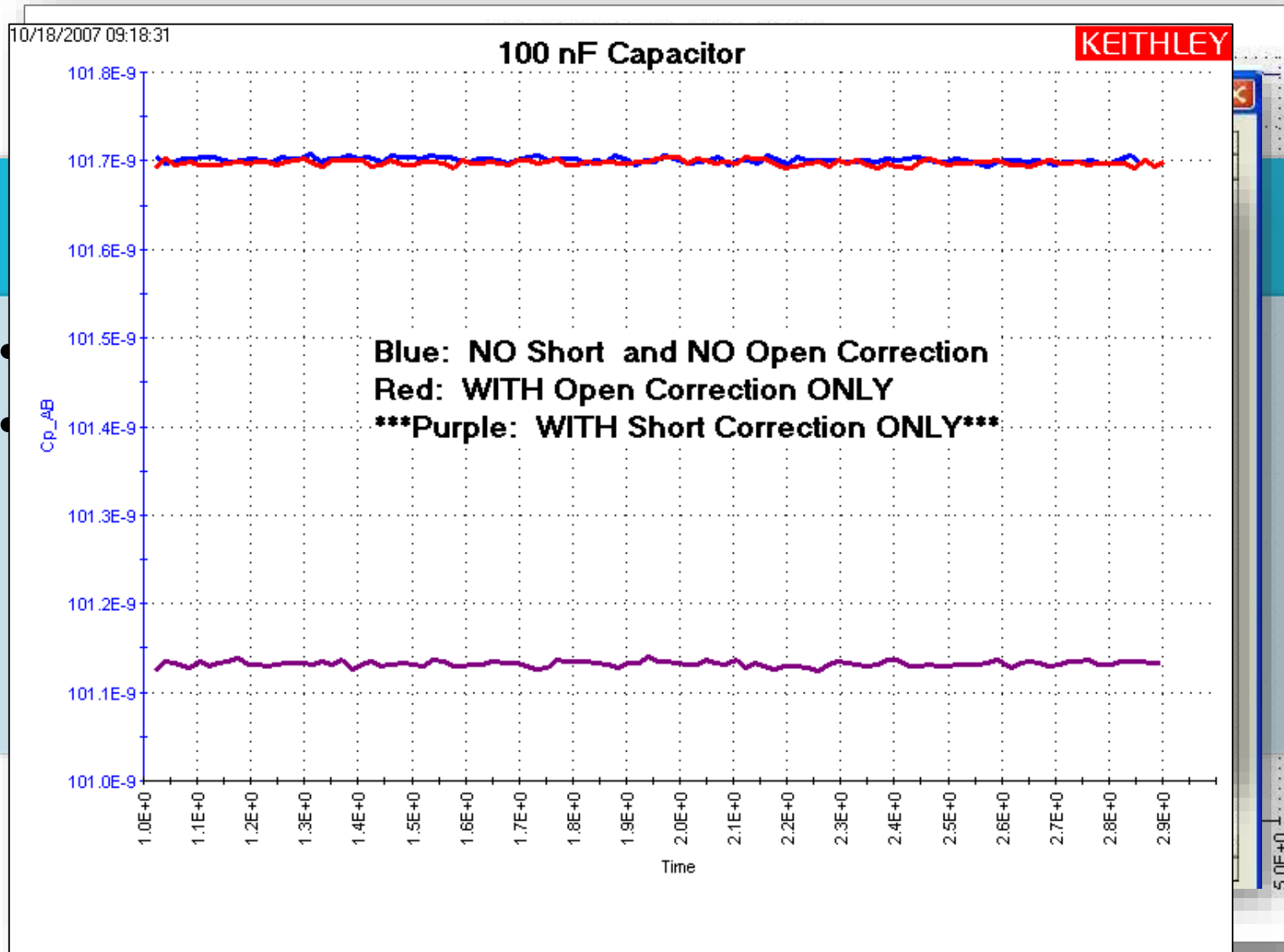
Compensation

Open/Short Correction



CV Curve of MOSFET

General Rule of Thumb



Confidence Check

CVU Confidence Check

CVU: CVU1

Real Time Measurement

| Cp | Gp |
|-----------------|---------------|
| 38.8e-12 | 4.6e-6 |

1uA Range (00000000)

Enable Parameters: Cp-Gp Settings...

Confidence Checks

Open Check Short Check

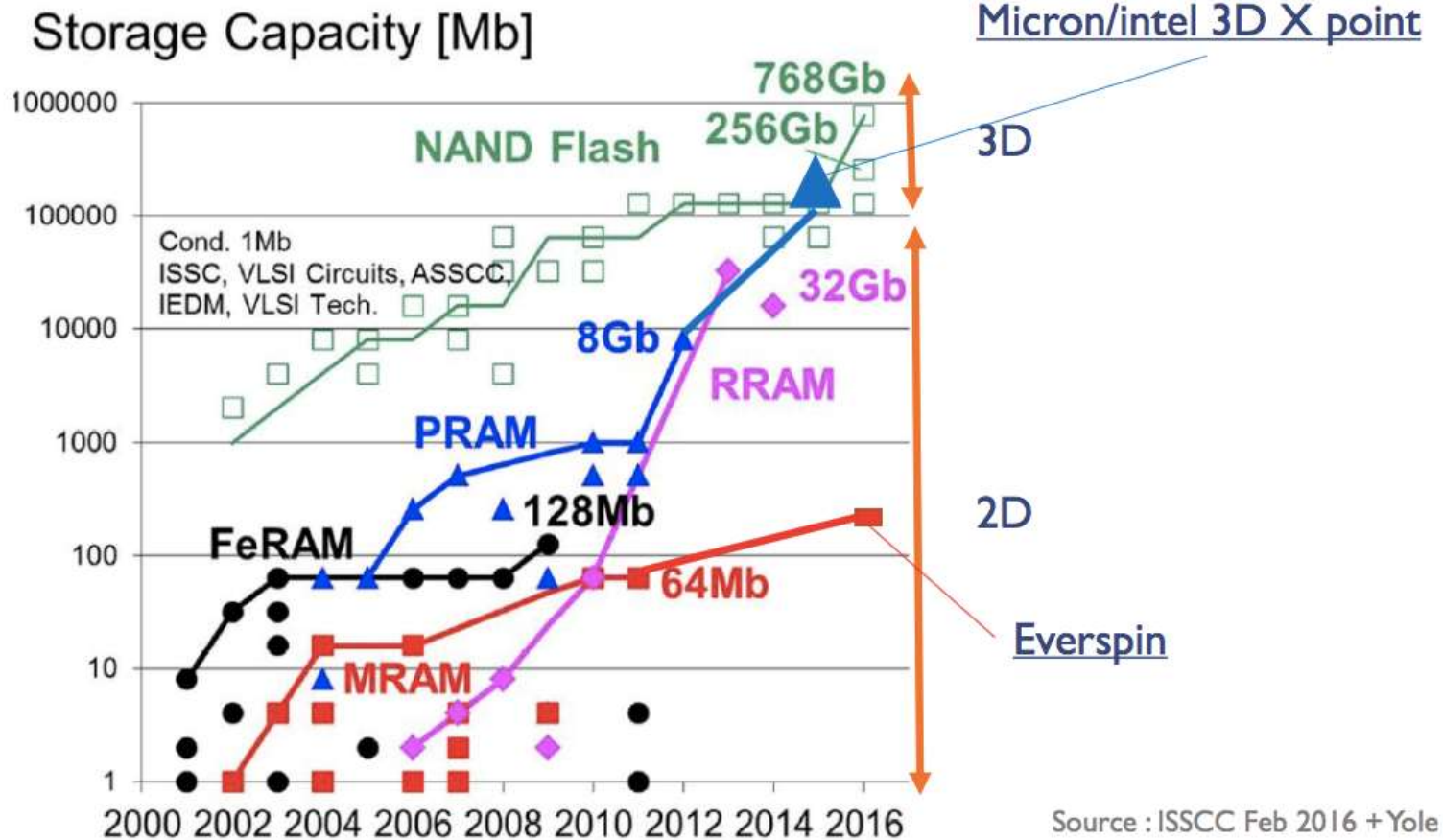
Confidence Check Status

OK Cancel

Memory → NVM

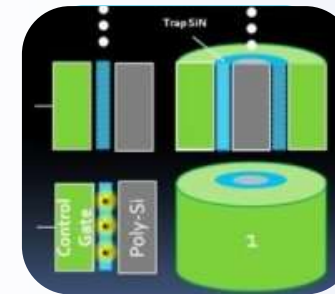
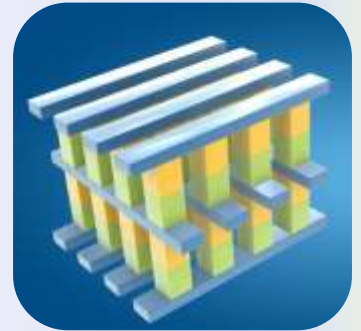


Memory: Where are we now



3D X point :

128 Gb chip, a density comparable to NAND, has been directly commercially presented (instead of R&D paper) by Micron/Intel in July 2015 in order to keep the technology secret until the last moment.



3D NAND Flash:

15.3 TB single disk is purchasable (released in 2016). Till now, it is the most leading applied memory in the consuming market.

A few key points about Memory



Speed:

Write/erase/ time should be less than 1ns for single cell operation. (Together with I/O design)



Capacity / Size

Single cell size should be as small as possible, ensure the capability for ultra-mass data/information storage.



Power

consumption

Lower operating voltage and leakage current to reduce the power consumption



Cost

Industrially process developing to decrease the cost of production (both for material and tools).

Memory: NVM performance between 2014

| 2014 | Emerging Memory | | | Established Memory | | |
|--|---------------------------|----------------------------|--------------------------|--------------------|---------------------------|------------------------------------|
| | STTMRAM | PCM | RRAM | SRAM | DRAM | Flash NAND |
| Non-Volatile | YES | YES | YES | NO | NO | YES |
| Endurance (Nb cycles) | High (10^{12}) | Medium (10^8) | Low (10^6) | High (10^{15}) | High (10^{15}) | Low (10^5) |
| 2014 latest technological node produced (nm) | 40nm 90 nm | 20nm 45 nm | 130 nm | 10 nm | 1nm 30 nm | 15 nm |
| Cell size (cell size in F ²) | Medium (6-12) | Medium (6-12) | Medium (6-12) | Very large (150) | Small (6-10) | Very small (4) |
| Write speed (ns) | High (10 ns) | Medium (75 ns) 50~100ns | High (20 ns) 20~250ns | High (5-10 ns) | High (10 ns) | Low (10,000 ns) |
| Power consumption | Medium/low | Medium | Low | Very low | Low | Very high |
| 2014 price (\$/Gb) | High (\$100-\$50/Gb) | Medium (few \$/Gb) | Very High (\$5,000/Gb) | Low (\$1/Gb) | Low (\$1/Gb) | Very low (\$0.05/Gb) |
| Suppliers | Everspin \$3000~200/GB | Micron, Samsung | Adesto \$100/GB | Qualcomm, Intel | Samsung, Micron, SK Hynix | Samsung, Micron, Toshiba, SK Hynix |

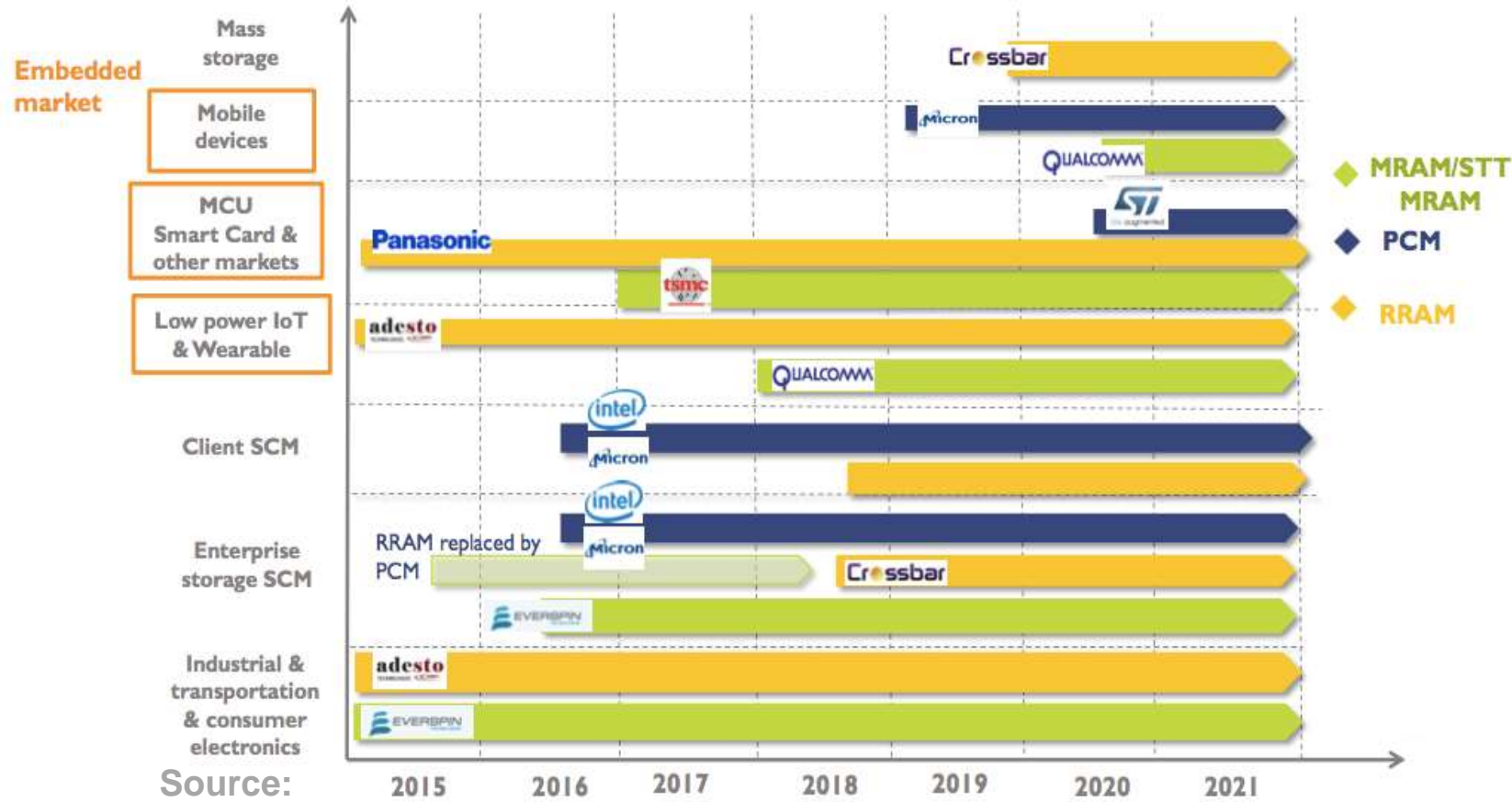
The new emerging NVM technology has changing in:
Cell size, Speed and Cost.

In the coming a few years, vast applications will be completely different due to the continues rapid developing of the NVM tech.

| 2016 | Emerging Memory | | | Established Memory | | |
|--|------------------------|-------------------|------------------|---------------------------|---|--|
| | STTMRAM | PCMS "3D Xpoint" | RRAM | DRAM | Flash NAND | |
| Non-Volatile | YES | YES | YES | NO | YES | |
| Endurance (Nb cycles) | High (10^{12}) | Medium (10^8) | Low (10^6) | High (10^{15}) | Low (10^5) | |
| 2016 latest technological node produced (nm) | 40 nm | 20 nm | 130 nm | 1X nm | 15 nm | |
| Cell size (cell size in F ²) | Medium (6-12) | ? | Medium (6-12) | Small (6-10) | Very small (4) | |
| Read latency (ns) | Fast (10-20 ns) | Fast (50-100 ns) | Medium (250 ns) | Very fast (few ns) | Slow (100,000 ns) | |
| Power consumption | Medium (50 pJ/bit) | Medium | Medium (6nJ/bit) | Low | Very high | |
| 2016 price (\$/Gb) | High (\$3000-\$200/Gb) | Low (\$ < 0.5/Gb) | High (\$100/Gb) | Low (< \$1/Gb) | Very low (\$ < 0.05/Gb) | |
| Suppliers | Everspin | Micron/Intel | Adesto | Samsung, Micron, SK Hynix | Samsung, Micron, Toshiba, SK Hynix, Intel | |

Source: Yole* These performance is all for commercial products and stand alone

Memory: The future market



Source: Yole

Emerging NVM market:

This whole market is just start to develop. No product available until 2015. Estimated : 2017:500M\$ → 2021:4500M \$

Promising emerging NVM:

Future mainstream technology is still to be chosen by the practical application. But there are two of them which considered as the most promising emerging NVM.

Memory: Two promising emerging NVM:



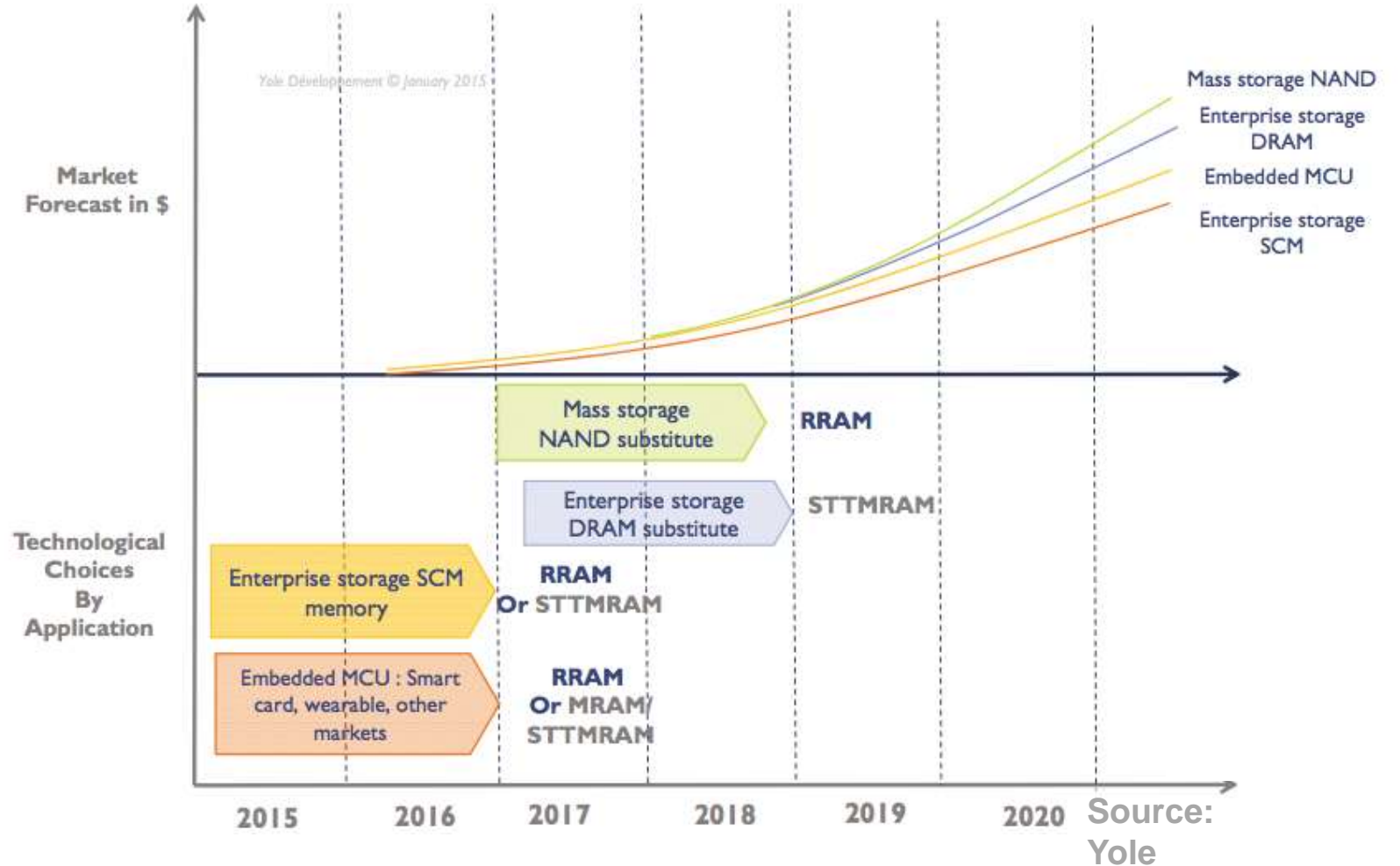
Mass storage

Mass storage purpose Memory and MCU may adopt new emerging NVM firstly within a few years.

Replacement

If the characteristics are confirmed and cost will not a problem, the new emerging NVM may replace SRAM/DRAM

The most promising 2 types of emerging NVM are RRAM and MRAM



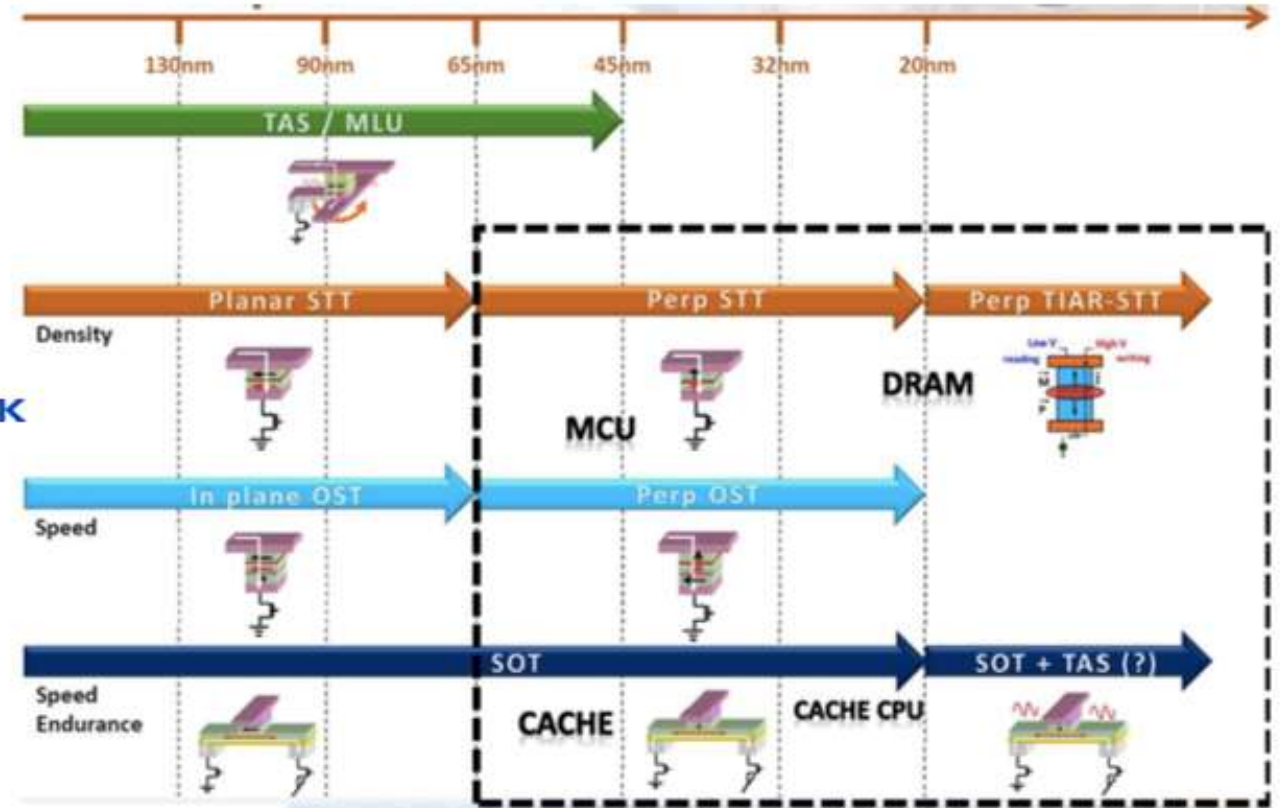
Memory: Two promising emerging NVM:



MRAM AND STTMRAM TECHNOLOGIES

Development status: production for low density, R&D for high density and embedded memory

MRAM market is dominated by Everspin (since 2006), which commercialized the first STTMRAM 64 Mb samples in Nov 2012 and 256 Mb in 2016 with two years delay. Avalanche also introduced with two years delay its 64 Mb product in 2016.



Source : Spintec June, 2014

Memory: Two promising emerging NVM:



RRAM TECHNOLOGIES

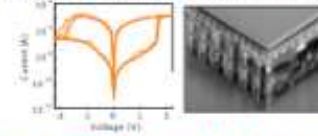
Development status: Stand-Alone devices : maximum chip density available

Main milestones will be 2018 for SCM enterprise storage with a lower pricing than 3D X point competitor and then, 2020 to compete with NAND

Ready for Commercialization

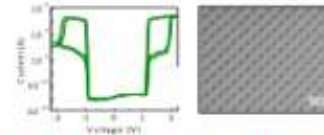


Demonstration of successful Crossbar RRAM + CMOS integration



✓ Proving our RRAM technology
Enabling cost-efficient fast read array

Demonstration of successful Selector + RRAM integration



✓ Proving scalability to ultra-high density and low power RRAM storage device
Solving the sneak path current challenge of crosspoint arrays

Source:
Crossbar

Memory test application example: RRAM test with 4200A

Measuring the 6th Wave

Project: resistive-nvm-examples

- do-rpm-ilimit-cal-1
- do-rpm-ilimit-cal-2
- Site 1 of 1
- reram
- reram-cell
- characterization
- forming
- butterfly-curve
- reram-endurance
- customdut
- customwaveform

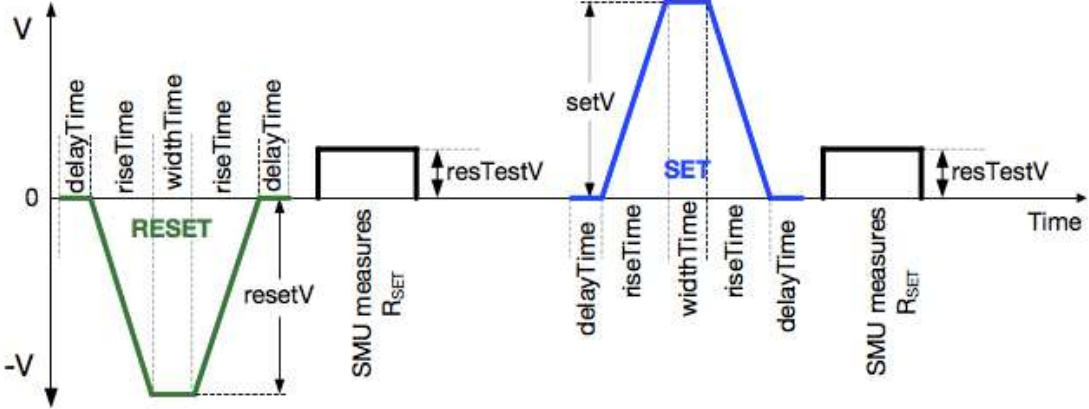
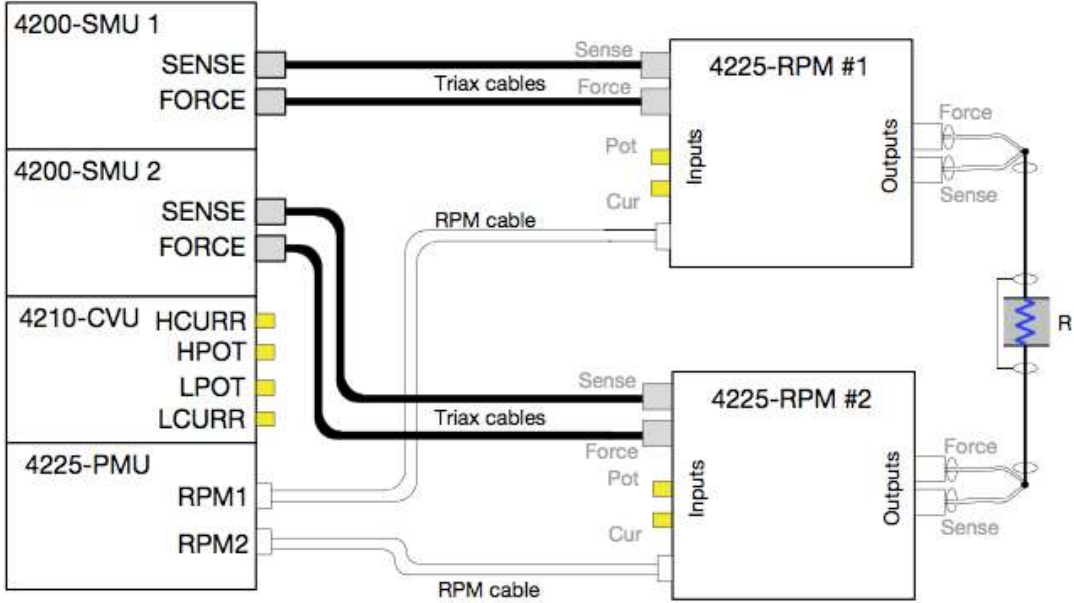


Figure 43. Pulse waveform with measure for *reramSweep* and *reramEndurance*.

Memory test application example: RRAM test

with

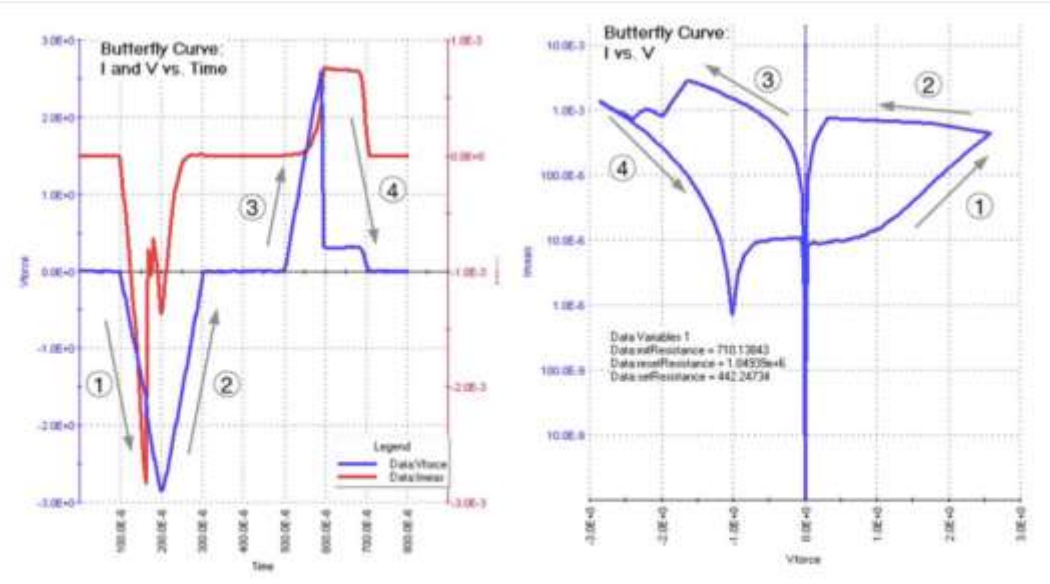


Figure 41. ReRAM "Butterfly" curve.

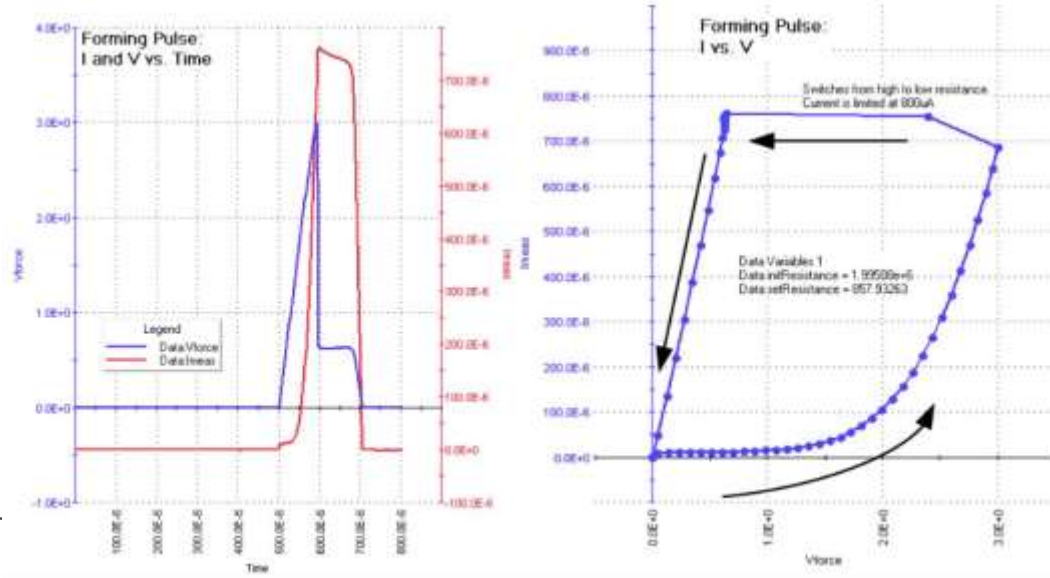


Figure 40. ReRAM forming.

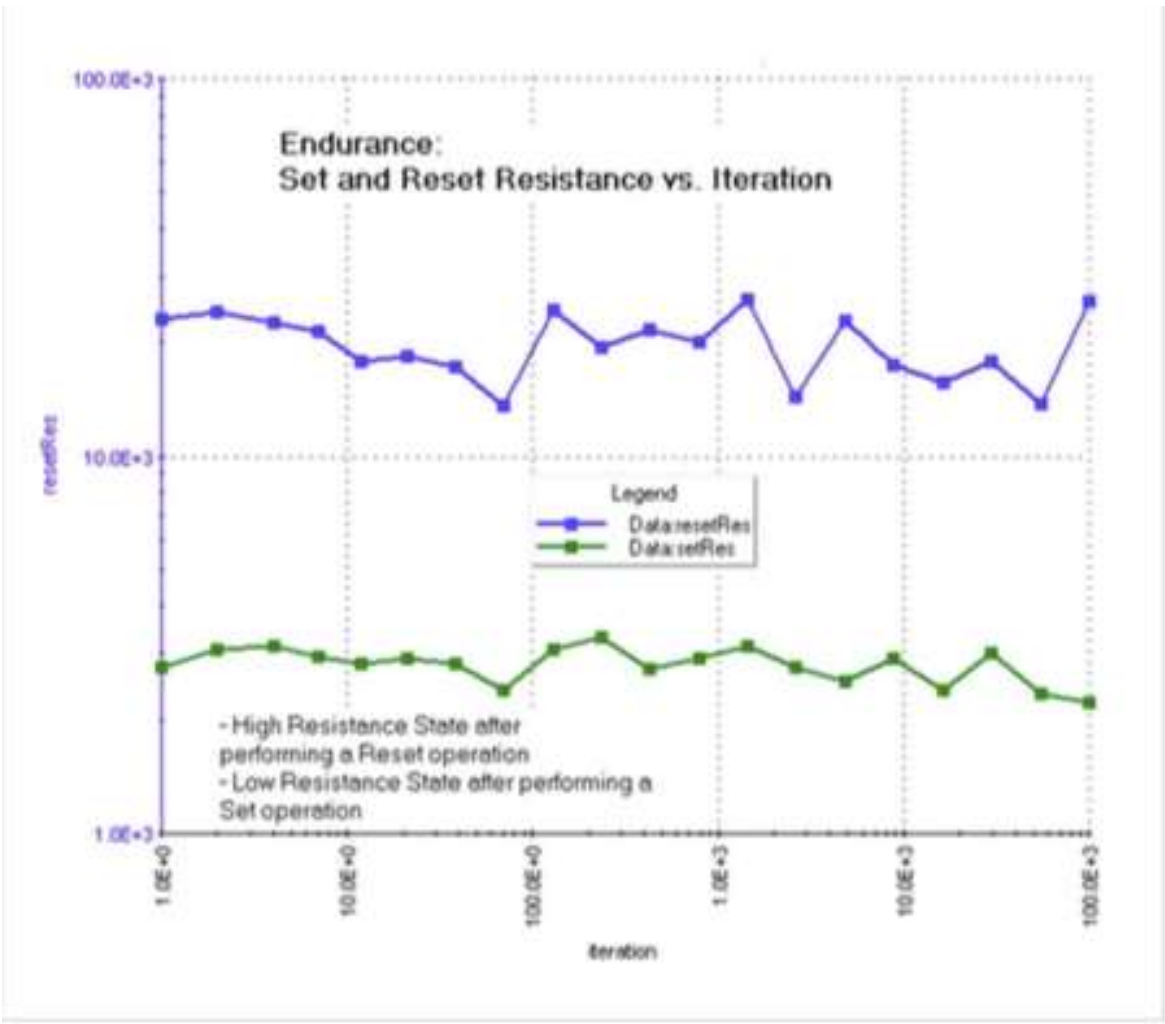


Figure 42: ReRAM endurance test.



Customized Software for NVM test

KEITHLEY SERVICE FOR SOFTWARE DESIGN

default

- 4terminal-n-fet
 - vds-id
 - vtlin
 - subvt
 - vgs-id
 - ig-vg
 - cv-nmosfet
 - pulse-vds-id
 - waveform-meas
- 3terminal-npn-bjt
 - vce-ic
 - gummel
 - vcsat
- 2-wire-resistor
 - Custom Test**
 - Custom Test_1
 - res2t
 - pulse-resistor

Custom Test#1

Key Parameters All Parameters

Test Settings Help

Custom Test#1

User Libraries: THU_RRAM

User Modules: Endurance2modes

Formulator Output Values

Gate Definition

Gate: PMU1-1

VWrite0Gate: 1 V

VWrite1Gate: 2 V

VReadGate: 5 V

DUTResGate: 1e+06 ohm

Pulse Definition

VRangeRead: 10 V

widthRead: 0.00015 s

auto set manual set

fallRead: 5e-06 s

Drain Definition

Drain: PMU1-2

DUTResDrain: 1e+06 ohm

VWrite1Drain: 2.5 V

VReadDrain: 0.1 V

Source Definition

Source: PMU2-1

VWrite0Source: 2.5 V

DUTResSource: 1e+06 ohm

R data collection

Rshift: 0 ohm

R0_delta: 1e+06 ohm

R1_delta: 1e+06 ohm

dataLogCycle: 100

maxCycle: 1000

readCycle: 10

modeLead: 0

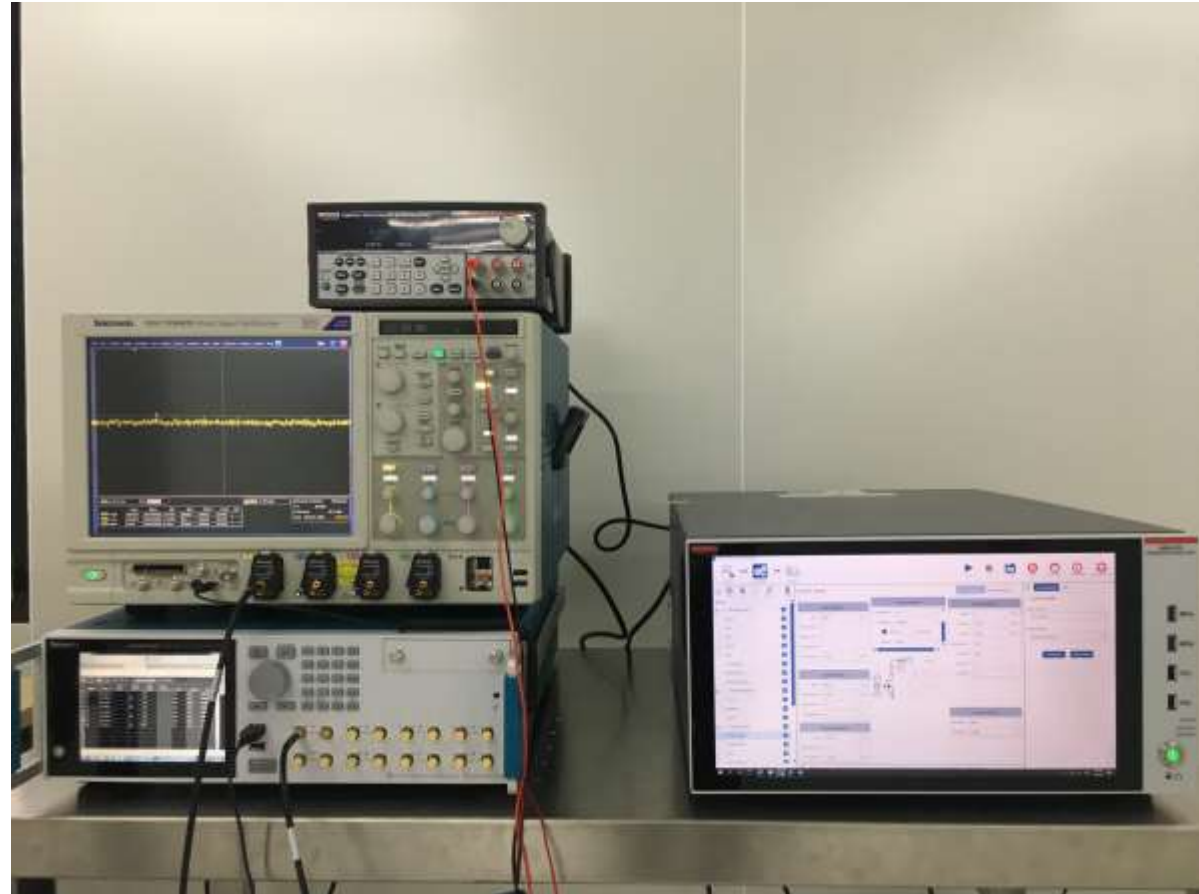
Measure Setting

measStart: 8e-05 s

measStop: 0.0001 s

Customized Software for NVM test

KEITHLEY SERVICE FOR SOFTWARE DESIGN



Example

2. 三端器件XXXXXXXXX特性测试 G,D,S三端

S端施加恒定电压，并不间断测量电流（电流采样频率可调）

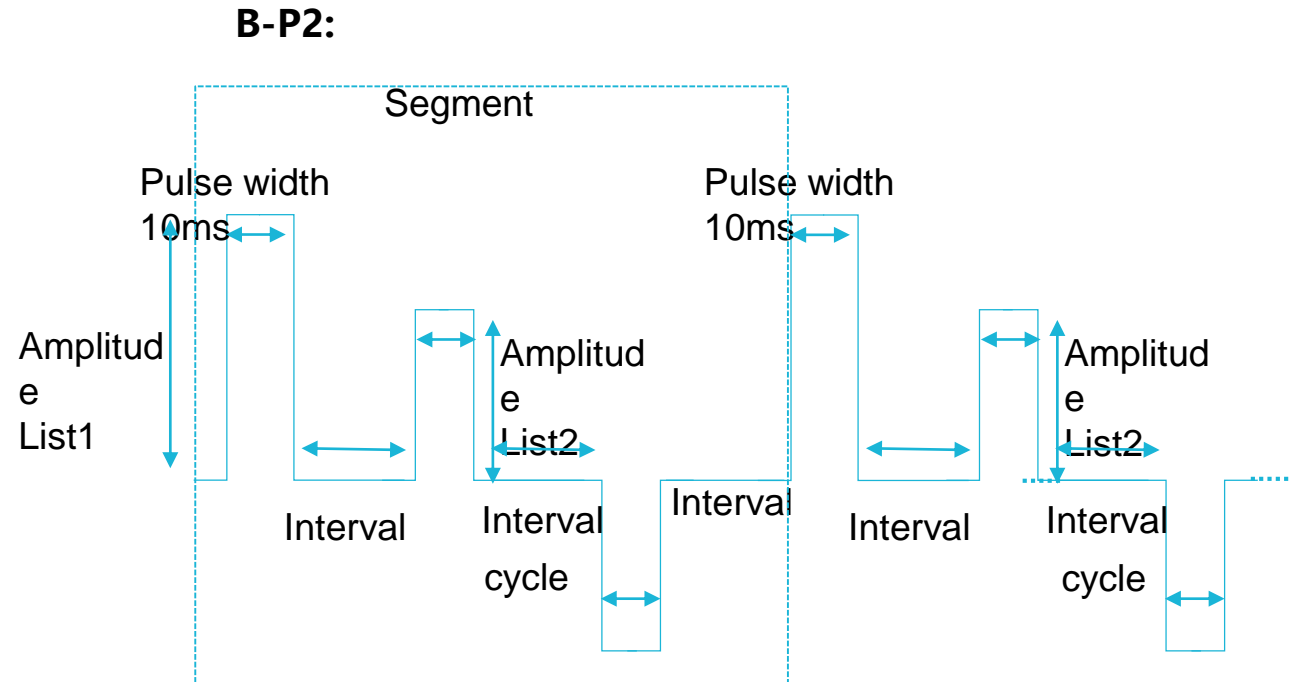
G端施加电压脉冲序列（脉冲幅度和脉宽可调）

D端接地；

3. 两端器件 (B-P1, B-P2可响应，只需设两端。不需硬件接地)

测试内容和三端一致，Top端施加脉冲信号/序列，Bottom端施加恒定电压并能不间断测量电流（电流采样频率可调）

只用PMU
Cycle < 1000



可调参数：

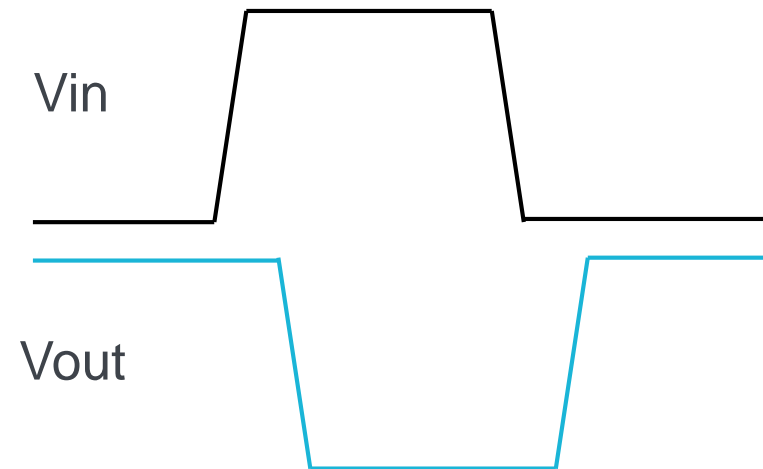
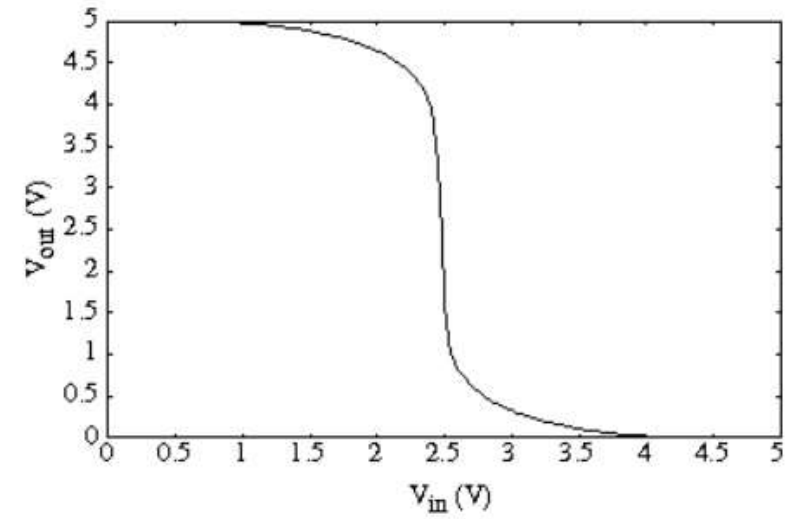
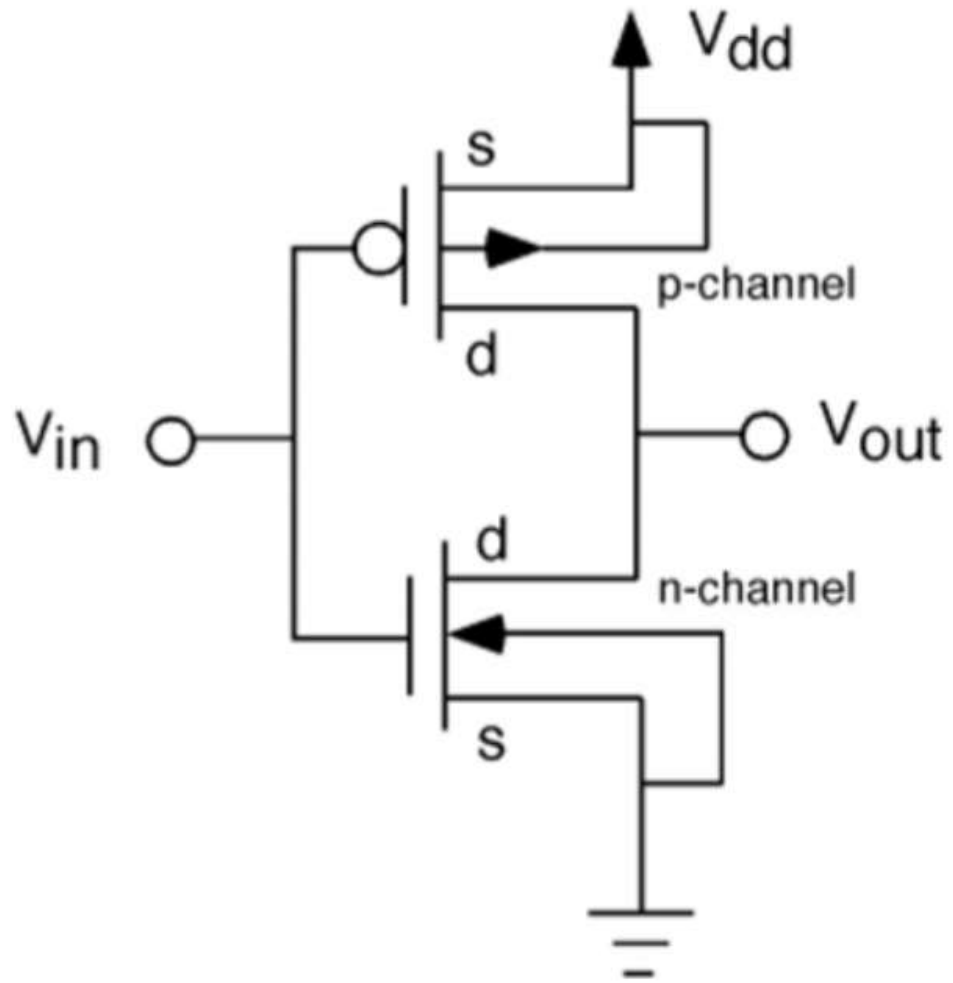
Channel assign → GDS → CH1,2

- a) 脉宽
- b) Amplitude list
- c) Interval
- d) Cycle Number
- e) 采样速率 (sample/s)
- f) S端电压 (另一channel DC)。

CMOS output character test

I-T/ V-T related test

CMOS test — ? vs. T test



CMOS test — ? vs. T test

KEY SETTINGS

Custom Test_2#1

Key Parameters All Parameters

Test Settings Terminal Settings Help

Custom Test2#1 Advanced

Measure Settings

Speed Normal

Report Timestamps

Test Mode

Mode Sweeping

Sweep Delay 0 s

Hold Time 0 s

Formulator Output Values Exit Condition

Messages 2018/04/23 - 03:18:31: riseRead= 0.000000e+00: Value must be from 2.000000e-08 to 1.000000e+00.

Time

List or Linear

Test setting

Terminal setting

SMU Advanced Test Settings

Measure Settings

Speed Normal

Delay Factor 1

Filter Factor 1

Auto A/D Algebras

Report Timestamps

Test Mode

Sweeping

Sweep Delay 0 s

Hold Time 0 s

SMU Power On Sequence

A

D

B

Move Up

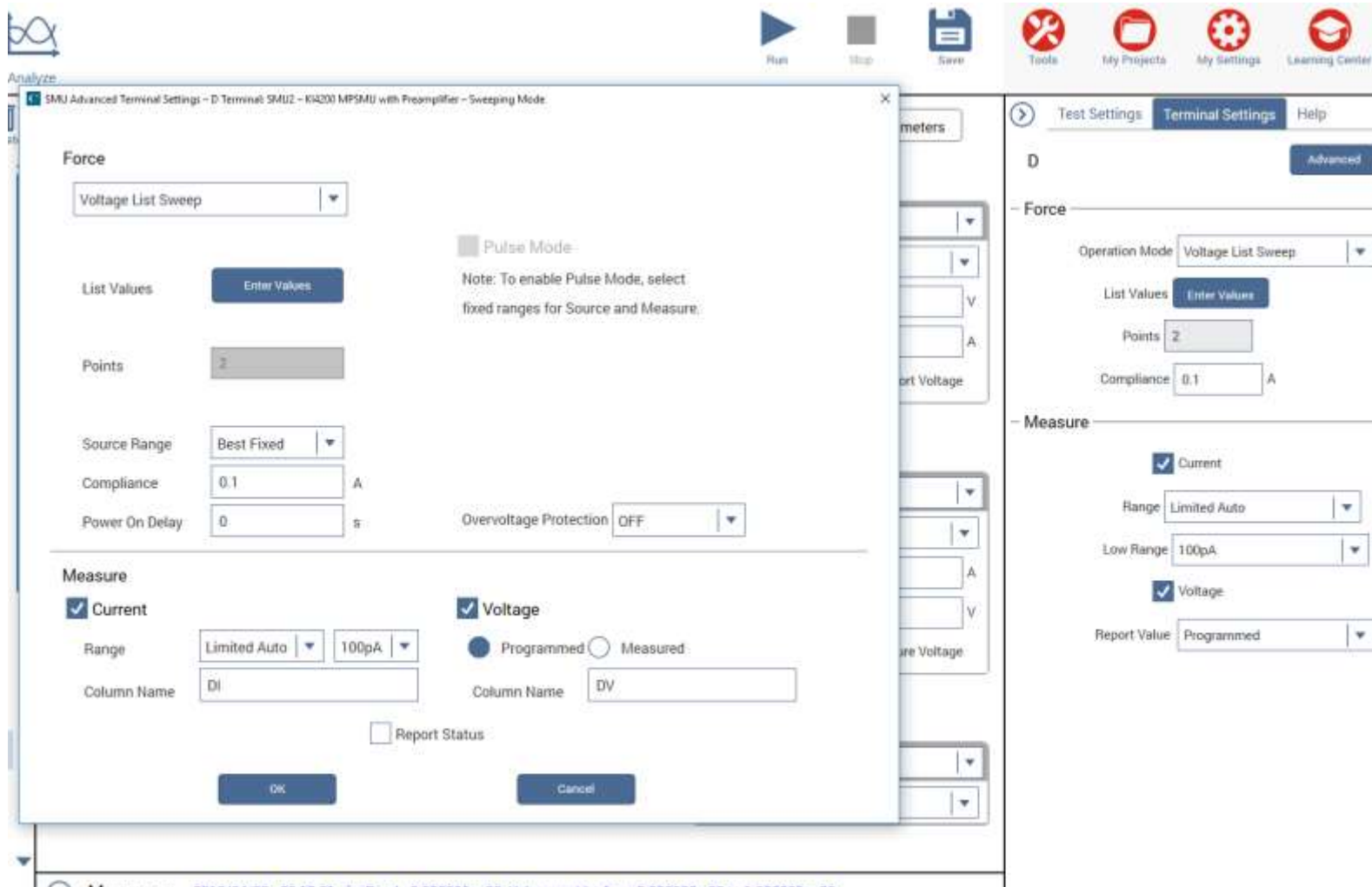
Move Down

Disable Outputs at Completion

OK Cancel

CMOS test — ? vs. T test

KEY SETTINGS

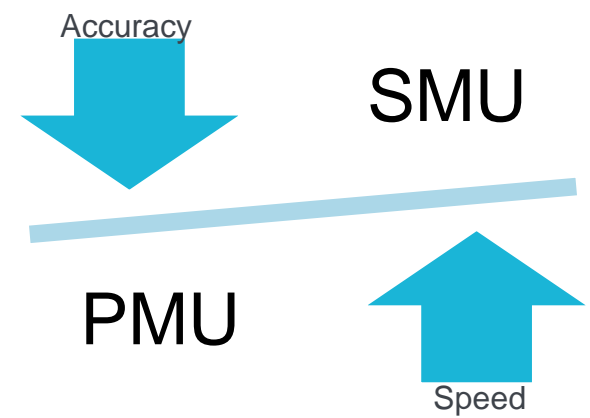


Time

List or Linear

Test setting

Terminal setting



WBG (wide band gap)

Wide Bandgap Semiconductors

- Wide bandgap semiconductors are materials that possess bandgaps significantly greater than those of silicon.
- Enable power electronic components to be:
 - Smaller
 - Faster
 - More reliable
 - More efficientthan their silicon-based counterpart devices.

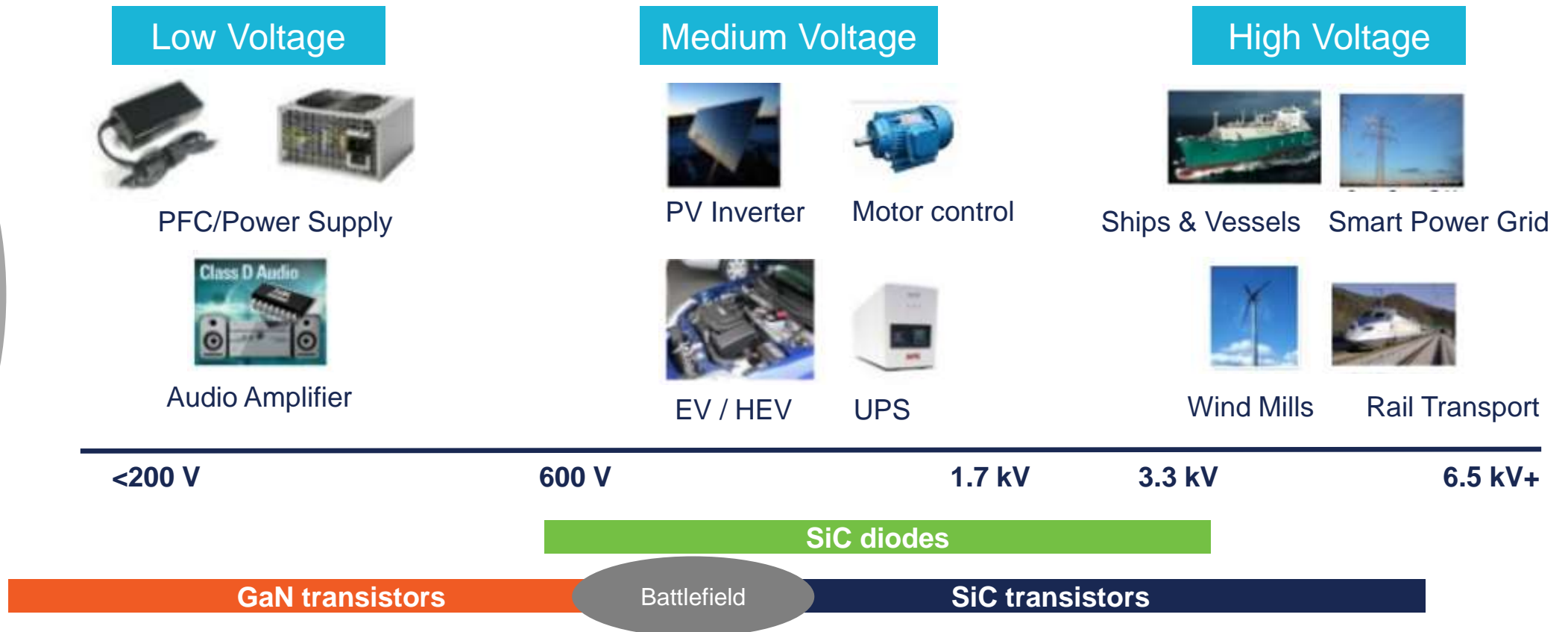
| Semiconductor Materials | | |
|-------------------------|-----------------|---------------------|
| Material | Chemical symbol | Bandgap Energy (eV) |
| Germanium | Ge | 0.7 |
| Silicon | Si | 1.1 |
| Gallium Arsenide | GaAs | 1.4 |
| Silicon Carbide | SiC | 3.3 |
| Zinc Oxide | ZnO | 3.4 |
| Gallium Nitride | GaN | 3.4 |
| Diamond | C | 5.5 |

End-Use Applications

WBG MARKET SEGMENTATION

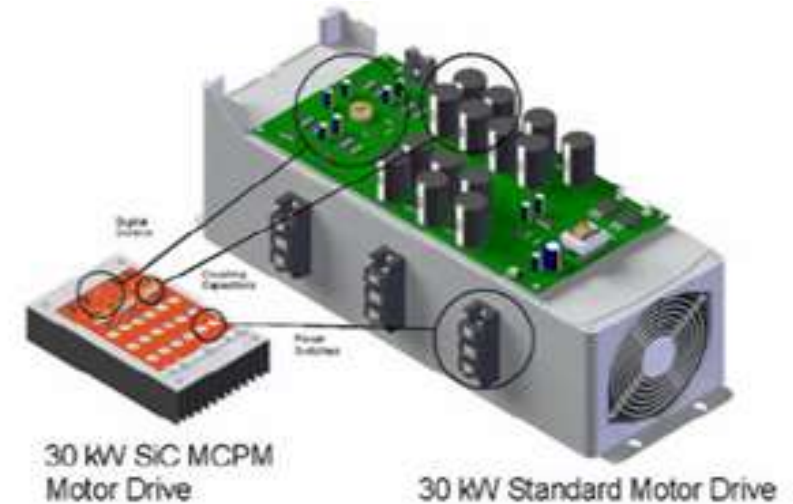
As a function of voltage range

While SiC is used for high voltage applications, GaN is mainly used for low voltage applications. 600-900V range will be the battlefield



Benefits of Wide Bandgap (WBG) Technology

- ~10X power density of Si
- < 1/2 Size
- Better higher temperature performance reduces or eliminates need for heat sinks
- Higher frequency results in lower losses during switching
- ~ Order of magnitude lower leakage current
- ~ Order of magnitude lower Rds-on



Technology Trends – GaN RF

- Massive increase in data rates is requiring technology updates to wireless network infrastructure (base stations) as well as evolution of cellular standard (movement to 5G)
- GaN RF is able to meet the higher frequency needs and power density needs
- Handheld RF devices
 - Government / Aerospace – GaN RF devices already used 28V – 48V
 - Consumer – Movement to 5G may necessitate research and spend on GaN RF devices in consumer handsets

| Traffic essentials | 2015 | 2016 | 2022 forecast | CAGR 2016 – 2022 | Unit |
|-----------------------------|------|------|---------------|------------------|-------|
| Data traffic per smartphone | 1.4 | 1.9 | 11 | 35% | GB/mo |
| Data traffic per mobile PC | 5.7 | 7.7 | 23 | 20% | GB/mo |
| Data traffic per tablet | 2.5 | 3.5 | 11 | 20% | GB/mo |
| Total mobile data traffic | 5.3 | 8.5 | 69 | 45% | EB/mo |
| Total fixed data traffic | 60 | 70 | 170 | 20% | EB/mo |

From Ericsson 2016 Mobility Report

WBG Challenges

- **Substrate size and cost:** producing larger diameter wafer at a lower cost is improving but further gains are needed.
- **Device design and cost:** novel device designs that effectively exploit the properties of WBG materials are needed to achieve current and voltage requirements of certain applications
- **Device measurements:** requires a wide dynamic range of instrumentation that combine High Speed AC, Low Level DC, and High Power
- **System integration:** WBG devices are not always suitable drop-in replacements for Si-based devices. Complex systems must be redesigned to integrate WBG.

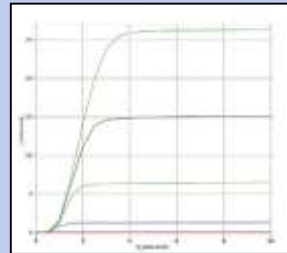
Typical WBG Tests

Testing WBG power devices requires **better resolution and faster speeds at higher power levels** compared to silicon, however the same basic tests are performed.

Testing falls into two main categories that we currently serve:

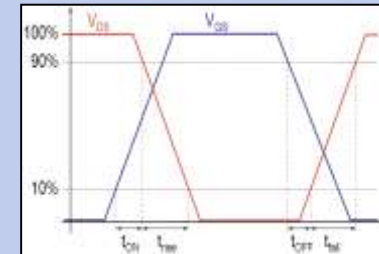
Static (DC) Testing: The customer's design goal is to optimize electrical performance in the ON and OFF states. An SMU instrument, System, or Parametric Curve Tracer is used to perform key tests such as:

- Breakdown Voltage
- Leakage Current
- On Resistance
- Characteristic Curves
- Capacitance

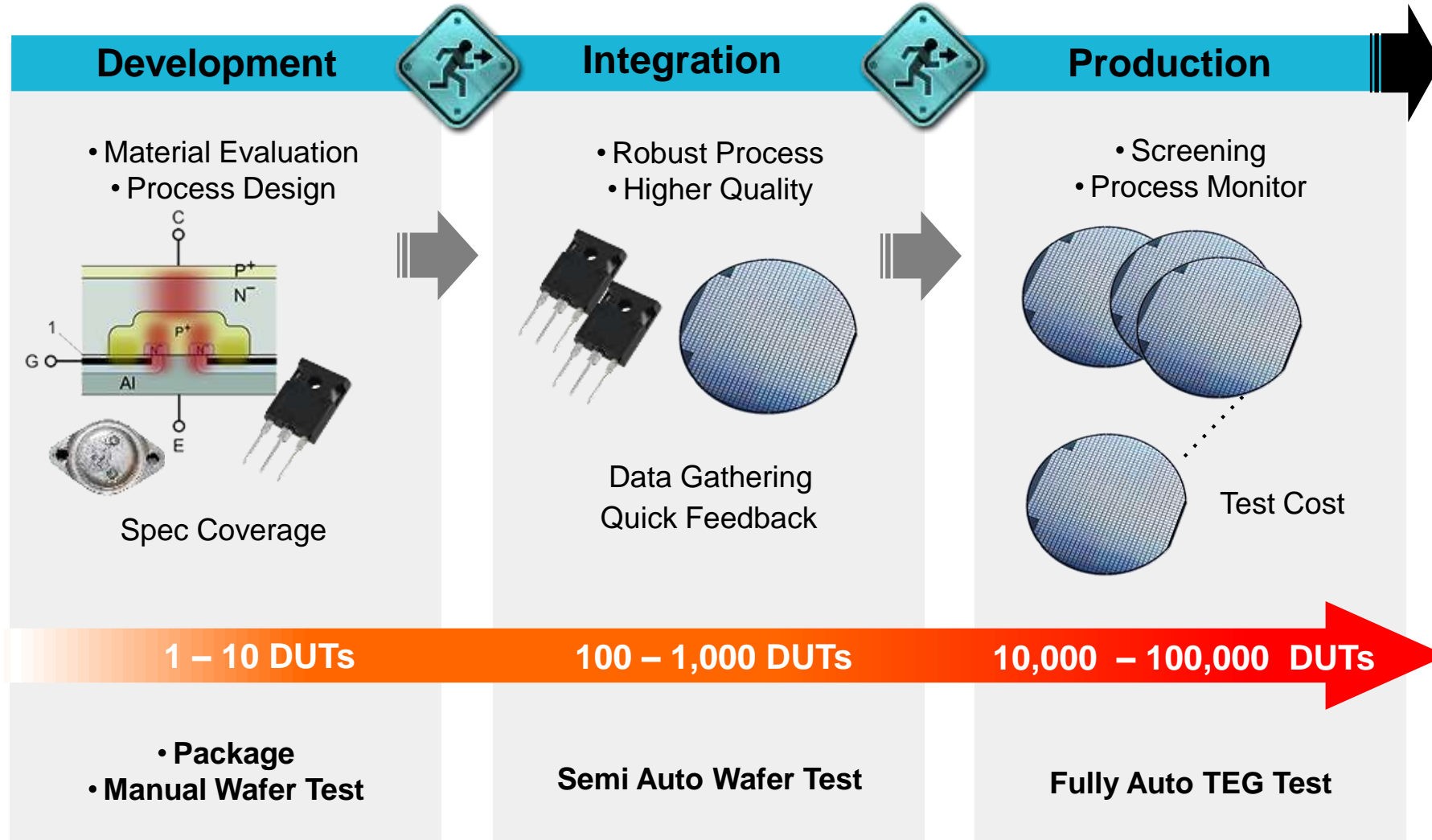


Dynamic (AC or Time Domain) Testing: The customer's design goal is to optimize switching times and perform comprehensive switching loss analysis. An Oscilloscope is used with Power Probes and an AFG to perform key tests such as:

- Turn-on / Turn-off times
- Rise and Fall times
- Recovery time



Path to High Volume Commercialization



S530 And S500

- 自动测试解决方案

软件



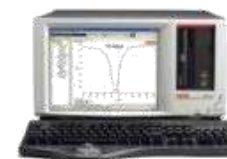
硬件



S530 Parametric Test System



S500 Integrated Test System

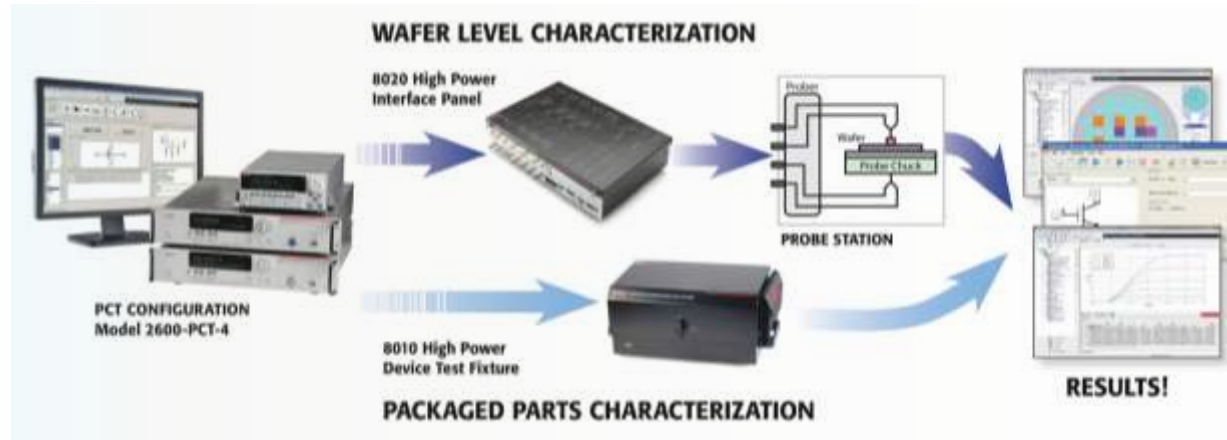


Instruments

配置标准化的测试系统

可根据实际情测试需求定制硬件及特殊测试程序

Power: Test application example



Manual
test for both wafer
level and package
level

Automated
wafer level parameter
test for both R&D
research and mass
production

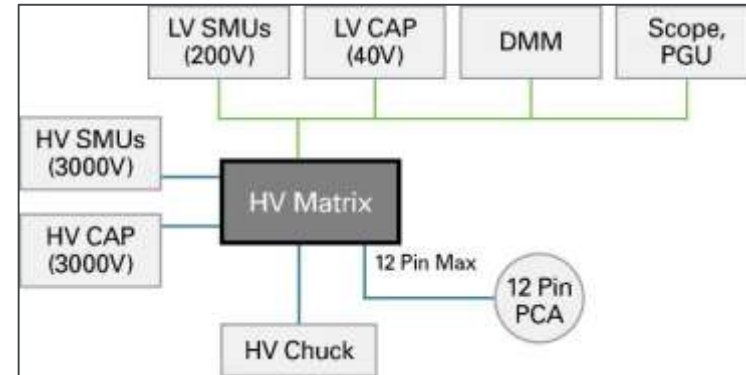


S540 Introduction

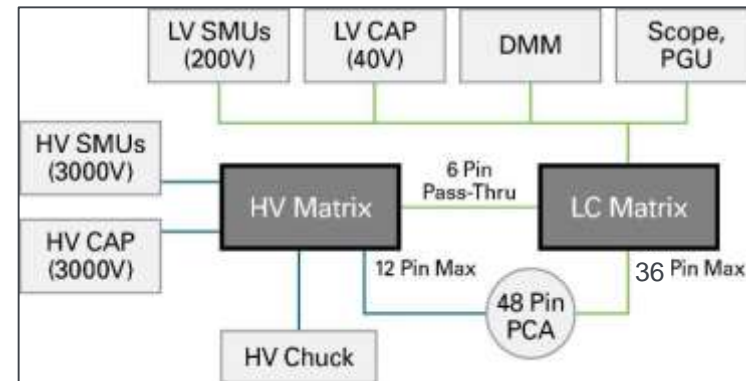
Industry's first 3KV automated parametric test system for wafer-level testing of power semiconductor.



- Eliminates the need to re-configure the test setup or use two separate test systems when moving from high voltage to low voltage tests
- Enables fully automated 2- or 3-terminal transistor capacitance measurements
- Delivers sub-pA level measurement performance in a standard, commercially available product.



12 Pin Configuration



24 - 48 Pin Configuration

S540 Introduction

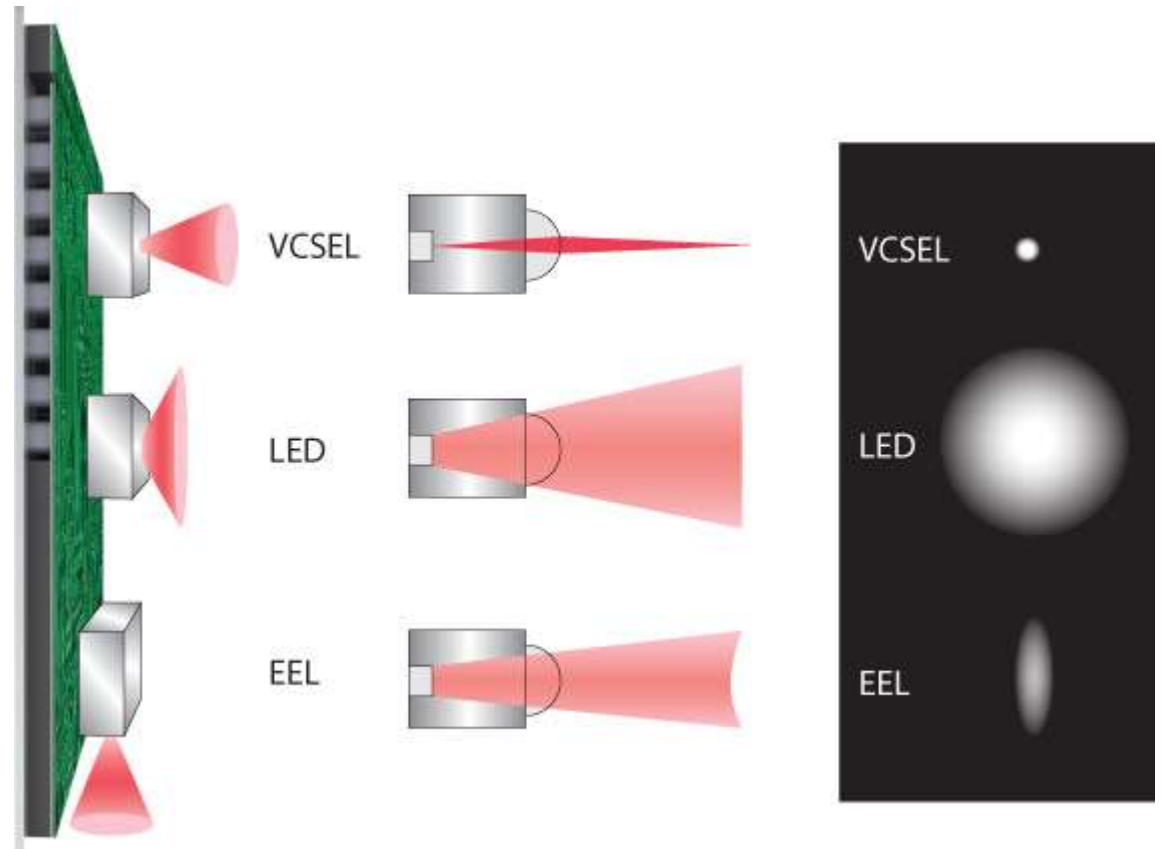
| Key Feature | Quantity Available |
|---|--------------------|
| Number of pins (full force-sense Kelvin): | |
| High Voltage (up to 3 kV using HV matrix) (includes 6 pin pass-thru from LC matrix) | 12 |
| Low Current (up to 200 V using 707B and 7531 matrix cards) | 0, 12, 24, or 36 |
| Number of SMU channels | |
| High Voltage (up to 3 kV using 2657A) | 1 or 2 |
| Low Voltage (up to 200 V using 2636B) (includes HV protection modules for each channel) | up to 8 |
| Capacitance Meter (using 4210-CVU) | |
| High Voltage (up to 3 kV, includes Bias-Ts) | 0 or 1 |
| Low Voltage (up to 30 V, includes protection modules) | 0 or 1 |
| High Resolution DMM (using 7510) | 0 or 1 |
| Pulse Generator (using 4220-PGU) | 0 or 1 |
| Oscilloscope (FMTR) | 0 or 1 |
| Industrial PC controller with Linux OS | 1 |
| KTE System Software | 1 |
| 37U System cabinet with 100–240 V, 50/60 Hz power distribution (PDU), emergency off (EMO) switch, high voltage interlock, and monitor/keyboard arm | 1 |
| Probe Card Adapter | |
| Keithley 9140 (48 pin maximum – 12 pin HV, 36 pin LV) Celadon (42 pin maximum – 12 pin HV, 30 pin LV) Customer Supplied | Choose One |

3D sensing

VCSEL Technology

VERTICAL CAVITY SURFACE EMITTING LASER

- Semiconductor-based laser diode that emits a highly efficient optical beam vertically from its top surface.
- Other common optical sources include Edge Emitting Lasers (EEL) that emit light from the side and Light Emitting Diodes (LED) that emit light from the top and sides.
- LEDs output a wide angle spectrum
- EEL emit elliptical beam



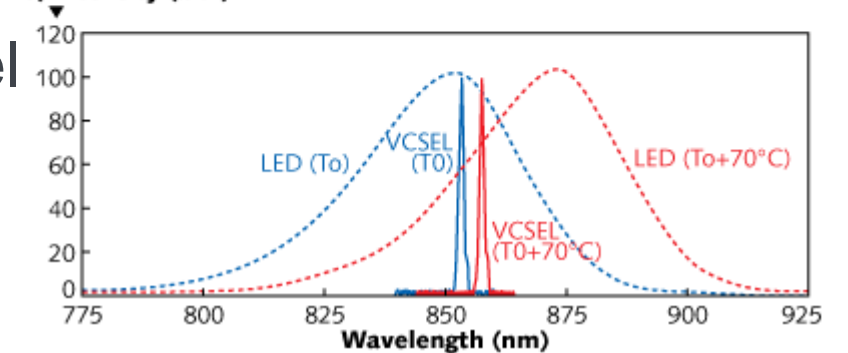
Advantages of VCSEL Technology

- Reliability: VCSELs don't have failure modes of traditional laser structures such as dark line defects.
- Manufacturability: able to use traditional semiconductor manufacturing equipment to keep fabrication costs low.
- Testability: can be completely tested at wafer level
This increases yield and lowers cost.

a) Comparison of infrared (IR) illumination sources

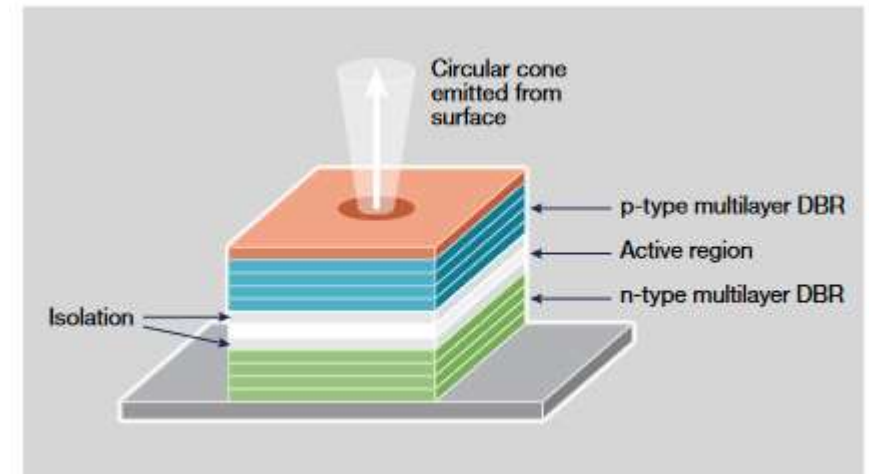
| Parameter | High-power IR LED | High-power IR VCSEL array | Edge-emitting laser |
|--------------------------------------|-------------------|---------------------------|---------------------|
| Low cost and manufacturability | ++ | + | - |
| Ease of packaging | + | + | - |
| Output power | - | + | ++ |
| Reliability | + | + | Neutral |
| Power conversion efficiency | Neutral | Neutral | + |
| Modulation speed | - | + | + |
| Emission beam and optics integration | - | + | - |
| Spectral properties | - | ++ | + |
| Speckle-free | + | + | - |

b) Intensity (a.u.)



VCSEL Technology Advantages

- Because VCSELs emit light perpendicular to the surface of the laser, tens of thousands of VCSELs can be processed on a single 3” wafer.
- VCSELs can also be tested at various stages of the manufacturing process while in wafer form, resulting in a more controlled and predictable yield with lower fabrication costs compared to other laser technologies.



3D Sensing & Gesture Recognition

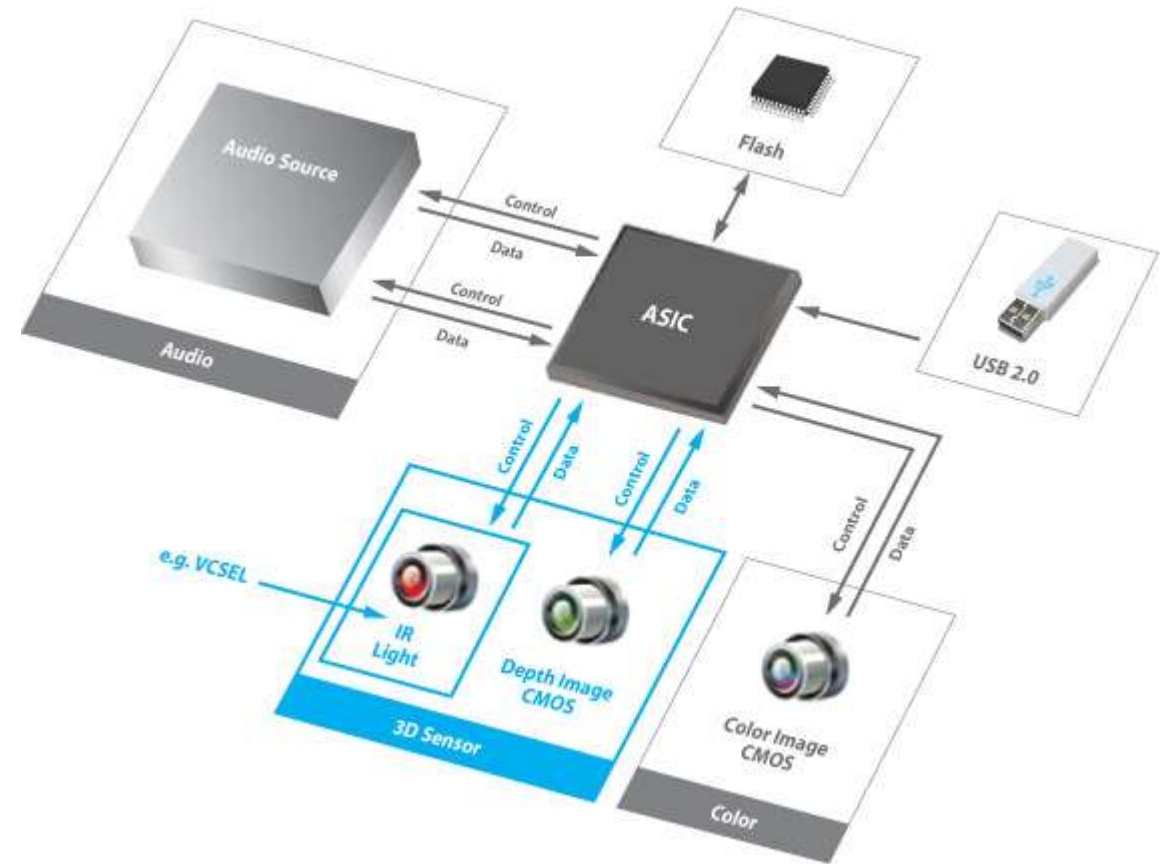
VCSEL APPLICATION

- 3D sensing enables autonomous, self-driving vehicles and lets the driver control infotainment systems more quickly and safely.
- 3D sensing systems transform the user interface for gaming and facial recognition in smartphones.
- In industrial equipment, 3D sensing allows operators to control computing equipment safely in hazardous environments.
- In future mobile devices, 3D sensing will augment camera capabilities to enable object recognition, depth data, greater precision, and object placement.



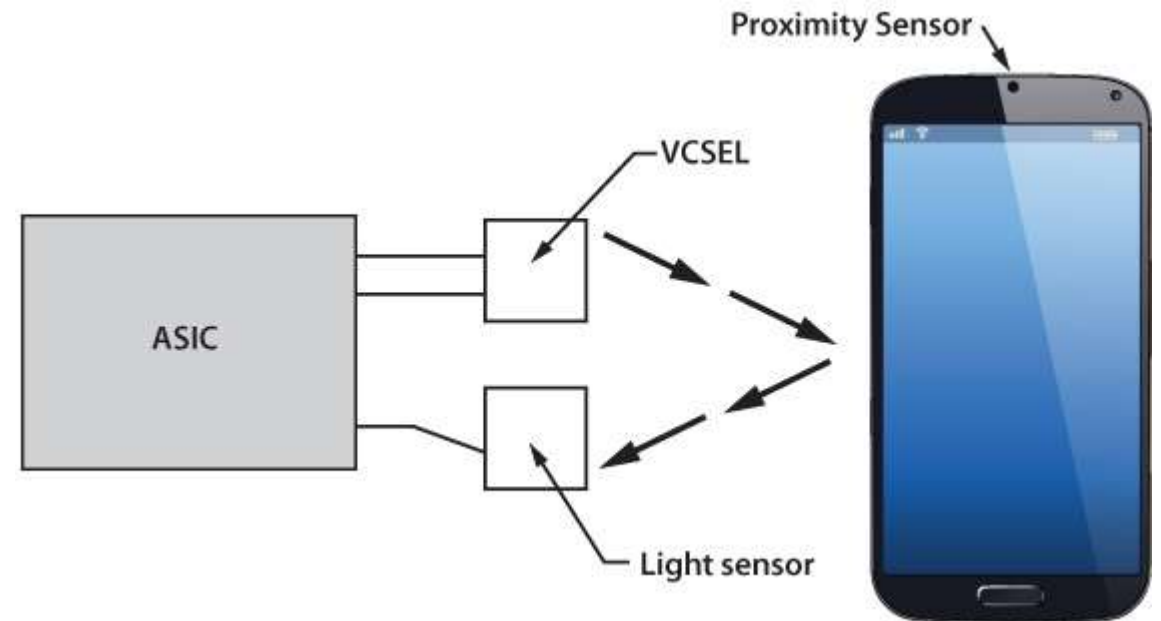
3D Sensing - Time of Flight

- To be able to detect movement across a living room, the detection system needs high power and precision.
- “Time of flight” tracking techniques flash a light pulse and track depth and motion by measuring the travel time of the light pulse from an object to an individual pixel on an image sensor.



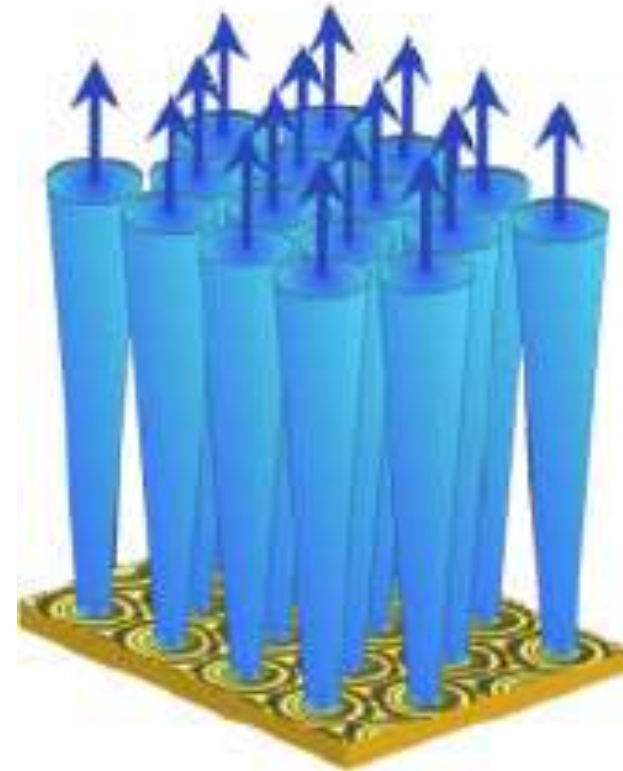
VCSEL Emerging Applications

- Proximity Sensing: measured by transmitting light and sensing reflections from nearby objects.
- Remote Power: use a light source to deliver energy to a sensor optically.
- Atomic Clocks: VCSELs reduce the form factor of a cesium or rubidium atomic clock down to a chip scale package.



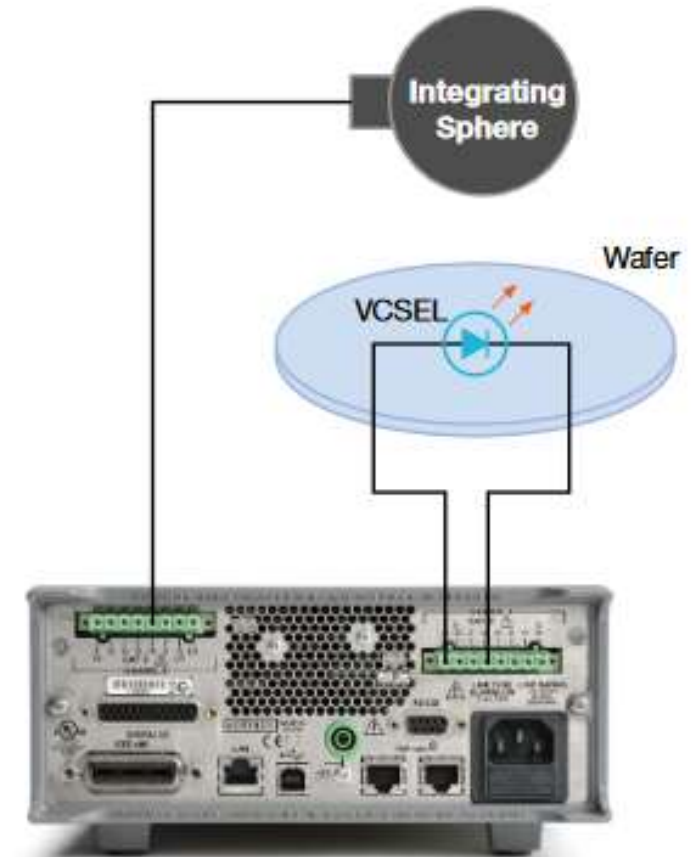
VCSEL Challenges

- **Manufacturing cost:** with the rapid expansion of VCSEL applications, there is demand for higher performance at a lower cost.
- **Device measurements:** in production, testing many VCSELs at once, at wafer level, is required to monitor performance and yield. Common measurements are both DC and optical testing.



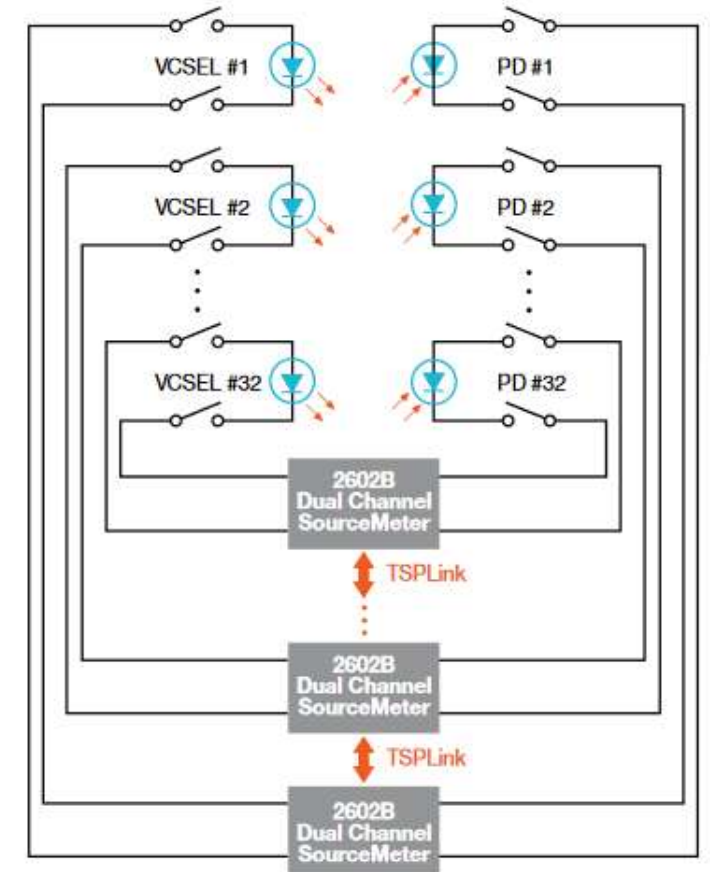
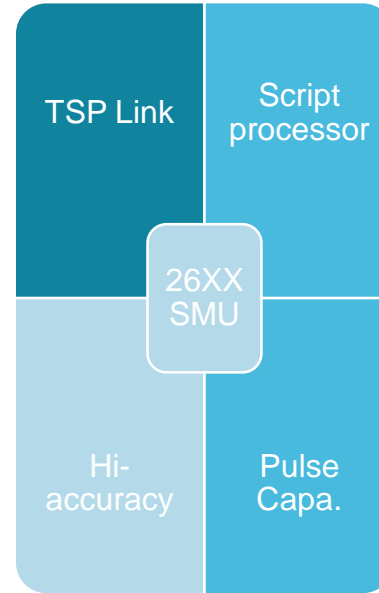
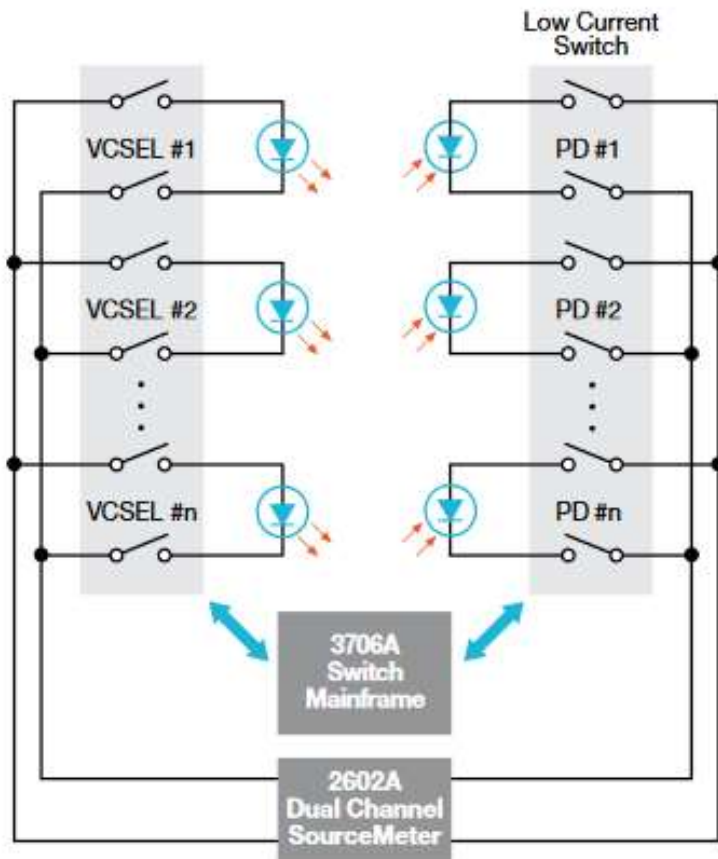
VCSEL Measurements

- During DC testing, the specifications of interest for the VCSEL module include:
 - Forward voltage
 - Kink test or slope efficiency (dL/dI)
 - Threshold current
 - Monitor (back facet) reverse-bias voltage
 - Monitor (back facet) current
 - Monitor (back facet) dark current
 - Optical output power



Meeting the Production Challenge

- Test multiple VCSELs using a switch and 2602B Source Measure Units.



- Test multiple VCSELs on wafer using a parallel test configuration using multiple 2602B Source Measure Units.